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Electronic component and electronic component module

Abstract

An electronic component includes an insulating layer, a low voltage conductor pattern formed inside the insulating layer, a high voltage conductor pattern formed inside the insulating layer such as to face the low voltage conductor pattern in an up/down direction, and a withstand voltage enhancement structure of conductive property formed inside the insulating layer and along the high voltage conductor pattern such as to protrude further outside than the low voltage conductor pattern in plan view.

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Background/Summary

CROSS-REFERENCE TO RELATED APPLICATIONS (1) The present application is a continuation of U.S. patent application Ser. No. 18/062,407, filed Dec. 6, 2022, which is a continuation of U.S. patent application Ser. No. 16/755,053, filed Apr. 9, 2020 (now U.S. Pat. No. 11,545,299), which is based on PCT filing PCT/JP2018/038365, filed Oct. 15, 2018, which claims priority to JP 2017-199877, filed Oct. 13, 2017, the entire contents of each are incorporated herein by reference.

TECHNICAL FIELD

(1) The present invention relates to an electronic component and an electronic component module.

BACKGROUND ART

(2) For example, in the field of power electronics, development of transformers having a pair of coils that are arranged to face each other is progressing. Patent Literature 1 discloses a transformer having a pair of inductors. One of the inductors is arranged to face the other inductor upon being rotated by 180° with a central axis as a rotational axis.

CITATION LIST

Patent Literature

(3) Patent Literature 1: Japanese Patent Application Publication No. 2013-115131

SUMMARY OF INVENTION

Technical Problem

(4) With an electronic component that includes a low voltage conductor pattern and a high voltage conductor pattern that face each other across an insulating layer, an electric field is formed in a region between the low voltage conductor pattern and the high voltage conductor pattern. The electric field tends to concentrate at the high voltage conductor pattern side. Occurrence of such concentration of electric field can be a detriment in terms of improving withstand voltage.

(5) A preferred embodiment of the present invention thus provides an electronic component and an electronic component module with which concentration of electric field on a high voltage conductor pattern is relaxed to enable improvement of withstand voltage.

Solution to Problem

(6) A preferred embodiment of the present invention provides an electronic component that includes an insulating layer, a low voltage conductor pattern formed inside the insulating layer, a high voltage conductor pattern formed inside the insulating layer such as to face the low voltage conductor pattern in an up/down direction, and a withstand voltage enhancement structure of conductive property formed inside the insulating layer and along the high voltage conductor pattern such as to protrude further outside than the low voltage conductor pattern in plan view.

(7) According to the present electronic component, concentration of electric field on the high voltage conductor pattern can be relaxed by the withstand voltage enhancement structure of conductive property. An electronic component that enables improvement of withstand voltage can thereby be provided.

(8) A preferred embodiment of the present invention provides an electronic component that includes an insulating layer, a low voltage conductor pattern formed inside the insulating layer, a high voltage conductor pattern formed inside the insulating layer such as to face the low voltage conductor pattern in an up/down direction, a low voltage pad formed on the insulating layer and electrically connected to the low voltage conductor pattern, a high voltage pad formed on the insulating layer at an interval from the low voltage pad in plan view and electrically connected to the high voltage conductor pattern, and a pad side withstand voltage enhancement structure of conductive property formed inside the insulating layer along a peripheral edge of the high voltage pad in plan view.

(9) According to the present electronic component, concentration of electric field on the high voltage pad can be relaxed by the pad side withstand voltage enhancement structure of conductive property. An electronic component that enables improvement of withstand voltage can thereby be provided.

(10) A preferred embodiment of the present invention provides an electronic component that includes a first insulating layer having a first dielectric breakdown strength, a low voltage conductor pattern formed inside the first insulating layer, a high voltage conductor pattern formed inside the first insulating layer such as to face the low voltage conductor pattern in an up/down direction, a low voltage wiring formed inside the first insulating layer at an interval from the high voltage conductor pattern in a direction along a front surface of the first insulating layer, electrically connected to the low voltage conductor pattern, and forming an electric field having a first value not more than the first dielectric breakdown strength between the high voltage conductor

pattern and the low voltage wiring, an electric field enhancement structure of conductive property interposed in a region between the high voltage conductor pattern and the low voltage wiring inside the first insulating layer, and forming an electric field having a second value not more than the first dielectric breakdown strength and not less than the first value between the low voltage wiring and the electric field enhancement structure, and a second insulating layer formed on the first insulating layer and having a second dielectric breakdown strength not more than the first dielectric breakdown strength.

(11) A case where the electric field enhancement structure is not formed shall now be considered. In this case, the high voltage conductor pattern is formed at a position close to the second insulating layer with respect to the low voltage conductor pattern. Therefore, an electric field concentrating on the high voltage conductor pattern is also a load for the second insulating layer. There is thus a possibility of dielectric breakdown occurring at the second insulating layer when an electric field strength at the high voltage conductor pattern exceeds the second dielectric breakdown strength of the second insulating layer.

(12) On the other hand, with the present electronic component, the electric field enhancement structure of conductive property is formed in the region inside the first insulating layer between the high voltage conductor pattern and the low voltage wiring. Thereby, an electric field between the high voltage conductor pattern and the low voltage wiring is practically determined by a distance between the electric field enhancement structure and the low voltage wiring.

(13) The concentration of electric field on the high voltage conductor pattern can thereby be relaxed. Moreover, an electric field that is formed between the low voltage conductor pattern and the high voltage conductor pattern can also be shielded by the electric field enhancement structure of conductive property.

(14) Therefore, while an electric field strength at the first insulating layer having the first dielectric breakdown strength that exceeds the second dielectric breakdown strength can be increased, an electric field strength at the second insulating layer having the second dielectric breakdown strength not more than the first dielectric breakdown strength can be decreased. That is, with the electronic component, the electric field strength at the second insulating layer side of low dielectric breakdown strength can be decreased by intentionally increasing the electric field strength at the first insulating layer side of high dielectric breakdown strength.

(15) Dielectric breakdown due to the concentration of electric field on the high voltage conductor pattern can thus be suppressed at the second insulating layer. An electronic component that enables improvement of withstand voltage can thus be provided.

(16) The aforementioned as well as yet other objects, features, and effects of the present invention will be made clear by the following description of the preferred embodiments, with reference to the accompanying drawings.

Description

BRIEF DESCRIPTION OF DRAWINGS

(1) FIG. 1 is a plan view of an electronic component module in which an electronic component according to a first preferred embodiment of the present invention is incorporated.

(2) FIG. 2 is a diagram of a connection configuration and potentials at respective portions of the electronic component module.

(3) FIG. 3 is a diagram for describing the planar structure of the electronic component.

(4) FIG. 4 is a diagram for describing the planar structure of a lower coil of the electronic component.

(5) FIG. 5 is a diagram for describing the planar structure of an upper coil of the electronic component.

- (6) FIG. 6 is a sectional view taken along line VI-VI in FIG. 3.
- (7) FIG. 7 is a sectional view taken along line VII-VII in FIG. 3.
- (8) FIG. 8 is a sectional view of the arrangement of a comparative mode of the electronic component.
- (9) FIG. 9 is a sectional view taken along line IX-IX in FIG. 8.
- (10) FIG. 10 is a graph comparing an average dielectric breakdown voltage of the electronic component according to the comparative mode of the present invention and an average dielectric breakdown voltage of the electronic component according to the first preferred embodiment of the present invention.
- (11) FIG. 11 is a graph comparing a variation of dielectric breakdown voltage of the electronic component according to the comparative mode of the present invention and a variation of dielectric breakdown voltage of the electronic component according to the first preferred embodiment of the present invention.
- (12) FIG. 12 is a diagram for describing the planar structure of upper coils of an electronic component according to a second preferred embodiment of the present invention.
- (13) FIG. 13 is an enlarged view of a region XIII shown in FIG. 12.
- (14) FIG. 14 is an enlarged view of a region XIV shown in FIG. 13.
- (15) FIG. 15 is an enlarged view of a region XV shown in FIG. 13.
- (16) FIG. 16 is a sectional view taken along line XVI-XVI shown in FIG. 12.
- (17) FIG. 17 is a sectional view taken along line XVII-XVII shown in FIG. 12.
- (18) FIG. 18 is a graph of a relationship between a protrusion amount of a first withstand voltage enhancement structure and electric field strength determined by simulation.
- (19) FIG. 19 is a graph of a relationship between the number of second dummy conductor patterns and electric field strength determined by simulation.
- (20) FIG. 20 is a graph comparing an average dielectric breakdown voltage of an electronic component according to a reference example of the present invention and an average dielectric breakdown voltage of the electronic component according to the second preferred embodiment of the present invention.
- (21) FIG. 21 is a diagram of a portion corresponding to FIG. 16 and is a sectional view of an electronic component according to a third preferred embodiment of the present invention.
- (22) FIG. 22 is a diagram of a portion corresponding to FIG. 14 and is a diagram for describing the planar structure at a first upper coil side of an electronic component according to a fourth preferred embodiment of the present invention.
- (23) FIG. 23 is a plan view of an upper coil of a sample of the electronic component shown in FIG. 22.
- (24) FIG. 24 is a plan view of an upper coil of a sample of the electronic component shown in FIG. 22.
- (25) FIG. 25 is a plan view of an upper coil of a sample of the electronic component shown in FIG. 22.
- (26) FIG. 26 is a graph of electric field strength measurement results of the sample shown in FIG. 23, the sample shown in FIG. 24, and the sample shown FIG. 25.
- (27) FIG. 27 is a graph comparing the average dielectric breakdown voltage of the electronic component according to the reference example of the present invention, an average dielectric breakdown voltage of the sample shown in FIG. 23, an average dielectric breakdown voltage of the sample shown in FIG. 24, and an average dielectric breakdown voltage of the sample shown in FIG. 25.
- (28) FIG. 28 is a sectional view for describing an electronic component according to a fifth preferred embodiment of the present invention.
- (29) FIG. 29 is a diagram for describing an effect of the electronic component shown in FIG. 28.
- (30) FIG. 30 is a diagram for describing the effect of the electronic component shown in FIG. 28.

- (31) FIG. **31** is a diagram for describing the planar structure of an electronic component according to a sixth preferred embodiment of the present invention.
- (32) FIG. **32** is a diagram for describing the planar structures of low voltage side capacitor conductor films of the electronic component shown in FIG. **31**.
- (33) FIG. **33** is a diagram for describing the planar structures of high voltage side capacitor conductor films of the electronic component shown in FIG. **31**.
- (34) FIG. **34** is a sectional view taken along line XXXIV-XXXIV shown in FIG. **31**.
- (35) FIG. **35** is a sectional view for describing an electronic component according to a seventh preferred embodiment of the present invention.
- (36) FIG. **36** is a diagram of a modification example related to a pattern of a resin film.
- (37) FIG. **37** is a diagram of a modification example related to a pattern of a resin film.
- (38) FIG. **38** is a plan view of an electronic component module according to a modification example.

DESCRIPTION OF EMBODIMENTS

- (39) FIG. **1** is a plan view of an electronic component module **1** in which an electronic component according to a first preferred embodiment of the present invention is incorporated. In FIG. **1**, a central portion of the electronic component module **1** is shown transparently for clarification of the internal structure.
- (40) There are cases where a high voltage pad electrically connected to a high voltage coil and a low voltage pad electrically connected to a low voltage coil are arranged apart in a lateral direction on a front surface of an electronic component.
- (41) Ordinarily, a distance between the low voltage pad and the high voltage pad is set to not less than several tens of times of a distance between the high voltage coil and the low voltage coil of a transformer from a standpoint of securing a sufficient withstand voltage. Therefore, sufficient examination has not been made up to now in regard to improving the withstand voltage by using a region between the low voltage pad and the high voltage pad.
- (42) Thus, with this embodiment, an electronic component and an electronic component module that enables improvement of the withstand voltage is provided upon making note of the region between the low voltage pad and the high voltage pad.
- (43) A package type of the electronic component module **1** is SOP (small outline package). The package type of the electronic component module **1** is not restricted to SOP and any of various types, such as QFP (quad flat package), SOJ (small outline J-lead package), etc., can be adopted as the package type of the electronic component module **1**.
- (44) The electronic component module **1** is a power module in which a plurality of chips are packaged in one package, and includes a resin package **2**, a plurality of leads **3**, and a plurality of chips **4**.
- (45) The resin package **2** is formed, for example, to a quadrilateral (square) plate shape using an epoxy resin. In this embodiment, the plurality of leads **3** are provided across an interior and an exterior of the resin package **2** via a pair of mutually facing end surfaces of the resin package **2**.
- (46) The plurality of chips **4** include a controller chip (controller IC) as an example of a low voltage device, an electronic component **6**, and a driver chip **7** (driver IC) as an example of a high voltage device. In this embodiment, the electronic component **6** is a transformer chip that includes transformers. Each of the chips **5** to **7** is formed to a quadrilateral (rectangular) plate shape.
- (47) The size of the controller chip **5** and the size of the driver chip **7** may be substantially equal. The electronic component **6** may be smaller in size than the controller chip and the driver chip **7**.
- (48) The electronic component **6** is arranged at a substantially central portion of the resin package **2**. The controller chip **5** and the driver chip **7** are respectively arranged at one of the lead **3** sides and at the opposite lead **3** side with respect to the electronic component **6**.
- (49) The controller chip **5** and the driver chip **7** are arranged such as to sandwich the electronic component **6** therebetween. The controller chip **5** and the driver chip **7** are each adjacent to a

plurality of the leads **3**.

(50) The controller chip **5** and the electronic component **6** are arranged on a first die pad **8** in common. The driver chip **7** is arranged on a second die pad **9** arranged at an interval from the first die pad **8**.

(51) A plurality of pads **10** and a plurality of pads **11** are formed on a front surface of the controller chip **5**. The plurality of pads **10** are aligned along a long side of the controller chip **5** at the side closer to the leads **3**. The plurality of pads **10** are connected by bonding wires **12** to the leads **3**.

(52) The plurality of pads **11** are aligned along a long side of the controller chip **5** at the side opposite to the leads **3** (the side closer to the electronic component **6**).

(53) A plurality of low voltage pads **13** and a plurality of high voltage pads **14** are formed on a front surface of the electronic component **6**. The plurality of low voltage pads **13** are aligned along a long side of the electronic component **6** at the side closer to the controller chip **5**. The plurality of low voltage pads **13** are connected to the pads **11** of the controller chip **5** by bonding wires **15**.

(54) In this embodiment, the pads **11** of the controller chip **5** are connected to a primary side of the electronic component **6**. The plurality of high voltage pads **14** are aligned along a long side of the electronic component **6** at a width direction central portion of the electronic component **6**.

(55) A plurality of pads **16** and a plurality of pads **17** are formed on a front surface of the driver chip **7**. The plurality of pads **16** are aligned along a long side of the driver chip **7** at the side closer to the electronic component **6**. The plurality of pads **16** are connected by bonding wires **18** to the high voltage pads **14** of the electronic component **6**.

(56) In this embodiment, the pads **16** of the driver chip **7** are connected to a secondary side of the electronic component **6**. The plurality of pads **17** are aligned along a long side of the driver chip **7** at the opposite side from the electronic component **6** (the side closer to the leads **3**). The plurality of pads **17** are connected by bonding wires **19** to the leads **3**.

(57) The positional configuration of the pads of the respective chips **5** to **7** shown in FIG. **1** is merely an example and can be changed as appropriate according to the package type and the positional configuration of the chips **4**.

(58) FIG. **2** is a diagram of a connection configuration and potentials at respective portions of the electronic component module **1** of FIG. **1**.

(59) As shown in FIG. **2**, with the electronic component module **1**, a lower coil **20** at the primary side (low voltage side) and an upper coil **21** at the secondary side (high voltage side) of the electronic component **6** face each other across an interval in an up/down direction.

(60) The lower coil **20** is formed as an example of a low voltage coil (low voltage conductor pattern). The upper coil **21** is formed as an example of a high voltage coil (high voltage conductor pattern). The lower coil **20** and the upper coil **21** are each formed to a spiral shape.

(61) A transformer (each of a first transformer **301** and a second transformer **302**) is formed by magnetic coupling of the lower coil **20** and the upper coil **21**. The controller chip and the driver chip **7** are DC isolated by the transformer (the lower coil **20** and the upper coil **21**). Also, the controller chip **5** and the driver chip **7** are AC connected by the transformer (the lower coil **20** and the upper coil **21**).

(62) A low voltage wiring **24** and a low voltage wiring **93** are respectively connected to an inner coil end **22** (inner terminal end of the spiral) and an outer coil end **92** (outer terminal end of the spiral) of the lower coil **20**. The terminal ends of the low voltage wirings **24** and **93** are exposed as the low voltage pads **13**.

(63) A high voltage wiring **25** (inner coil end wiring) and a high voltage wiring **95** (outer coil end wiring) are respectively connected to an inner coil end **23** and an outer coil end **94** of the upper coil **21**. The terminal ends of the high voltage wirings **25** and **95** are exposed as the high voltage pads **14**.

(64) The controller chip **5** includes transistors Tr**1** and Tr**2**. The transistors Tr**1** and Tr**2** are switching devices that perform conductive connection and interruption of wirings **90** and **91**,

respectively.

(65) The transistor Tr1 is provided in the middle of the wiring **90** that connects a certain pad **10** and a certain pad **11**. The transistor Tr2 is provided in the middle of the wiring **91** that connects another pad **10** and another pad **11**.

(66) The pads **10** and **11** at the wiring **90** side are connected to an input voltage and the low voltage pads **13** at the outer coil end **92** side through bonding wires **12** and **15**, respectively. The pads **10** and **11** at the wiring **91** side are connected to a ground voltage and the low voltage pads **13** at the inner coil end **22** side through bonding wires **12** and **15**, respectively.

(67) By controlling the controller chip **5** such that a first voltage application state (Tr1: ON, Tr2: OFF) and a second voltage application state (Tr1: OFF, Tr2: ON) are repeated alternately, a periodic pulse voltage is generated in the lower coil **20** of the electronic component **6**. For example, in FIG. **2**, a pulse voltage of 5 V with respect to a reference voltage=0 V (ground voltage) is generated in the lower coil **20**.

(68) With the electronic component **6**, while a DC signal is interrupted between the lower coil **20** and the upper coil **21**, just an AC signal based on the pulse voltage generated in the lower coil **20** is selectively transmitted to the high voltage side (upper coil **21**) by electromagnetic induction.

(69) The transmitted AC signal is boosted in accordance with a transformer ratio between the lower coil **20** and the upper coil **21**. The transmitted AC signal is output to the driver chip **7** through the bonding wires **18**. For example, in FIG. **2**, after the pulse voltage of 5 V is boosted to 15 V, it is output to the driver chip **7** with which a reference voltage is set to 1200 V.

(70) The driver chip **7** applies the input pulse voltage of 15 V to a gate electrode (not shown) of an SiC power MOSFET (for example, source-drain voltage=1200 V) to perform switching operation of the MOSFET.

(71) The specific voltage values shown in FIG. **2** are merely an example used for describing an operation of the electronic component module **1**. The reference voltage of the driver chip **7** (HV region) may be a value that exceeds 1200 V.

(72) FIG. **3** is a diagram for describing the planar structure of the electronic component **6**. FIG. **4** is a diagram for describing the planar structure of a layer of the electronic component **6** at which the lower coil **20** is arranged. FIG. **5** is a diagram for describing the planar structure of a layer of the electronic component **6** at which the upper coil **21** is arranged.

(73) FIG. **6** is a sectional view of the electronic component **6** (sectional view taken along line VI-VI in FIG. **3**). FIG. **7** is a sectional view of the electronic component **6** (sectional view taken along line VII-VII in FIG. **3**). In FIG. **6** and FIG. **7**, just metal portions are applied with hatching for clarification.

(74) Referring to FIG. **3** to FIG. **5**, the electronic component **6** includes the first transformer **301** and the second transformer **302**. The first transformer **301** and the second transformer **302** are formed at an interval along a length direction of the electronic component **6**. On sheet surfaces of FIG. **3** to FIG. **5**, the first transformer **301** is shown at an upper side and the second transformer **302** is shown at a lower side.

(75) As shall be described below, the first transformer **301** includes two sets each of the lower coil **20** and the upper coil **21** that face each other. Similarly, the second transformer **302** includes two sets each of the lower coil **20** and the upper coil **21** that face each other.

(76) As shown in FIG. **6** and FIG. **7**, a semiconductor substrate **26** and an insulating layer laminated structure **27** formed on the semiconductor substrate **26** are included. As the semiconductor substrate **26**, an Si (silicon) substrate, an SiC (silicon carbide) substrate, etc., can be applied.

(77) By the semiconductor substrate **26**, the electronic component **6** is formed as a semiconductor device. The electronic component module **1** that includes the electronic component **6** is thus formed as a semiconductor module.

(78) The insulating layer laminated structure **27** is constituted of a plurality (twelve layers in FIG. **6**

and FIG. 7) of insulating layers **28** that are laminated successively from a front surface of the semiconductor substrate **26**. With the exception of the insulating layer **28** that is the lowermost layer contacting the front surface of the semiconductor substrate **26**, the plurality of insulating layers **28** are each constituted of a laminated structure of an etching stopper film **29** that is a lower layer and an interlayer insulating film **30** that is an upper layer.

(79) The insulating layer **28** that is the lowermost layer is constituted of just the interlayer insulating film **30**. As the etching stopper film **29**, an SiN film, an SiC film, an SiCN film, etc., may be used. As the interlayer insulating film **30**, an SiO₂ film may be used.

(80) The lower coil **20** and the upper coil **21** are formed in mutually different insulating layers **28** in the insulating layer laminated structure **27**. The lower coil **20** and the upper coil **21** face each other across one layer or more of the insulating layers **28**.

(81) In this embodiment, the lower coil **20** is formed in the insulating layer **28** that is the fourth layer from the semiconductor substrate **26**. The upper coil **21** is formed in the eleventh insulating layer **28** with six layers of the insulating layers **28** between the upper coil **21** and the lower coil **20**.

(82) As shown in FIG. 3 to FIG. 5, each lower coil **20** and each upper coil **21** are formed in regions of elliptical annular shapes that surround peripheries of inner regions **31** and **32**, respectively, of elliptical shape in plan view such as to demarcate the inner regions **31** and **32** at centers thereof.

(83) Each upper coil **21** is formed such that its upper surface is flush with an upper surface of an insulating layer **28**. The upper coil **21** is thereby in contact with mutually different insulating layers **28** at its side surface, upper surface, and lower surface.

(84) Specifically, with the insulating layer **28** in which the upper coil **21** is embedded, the etching stopper film **29** and the interlayer insulating film **30** are in contact with the side surface of the upper coil **21**. With the interlayer insulating film **28** formed at an upper side of the insulating layer **28** in which the upper coil **21** is embedded, just the etching stopper film **29** that is the lower layer contacts the upper surface of the upper coil **21**. With the insulating layer **28** at the lower side, just the interlayer insulating film **30** that is the upper layer contacts the lower surface of the upper coil **21**.

(85) Although description shall be omitted here, as with the upper coil **21**, the lower coil **20** is also formed such that its upper surface is flush with an upper surface of an insulating layer **28**.

(86) As shown in FIG. 3, FIG. 6, and FIG. 7, high voltage pad layers **88** as examples of high voltage conducting layers and low voltage pad layers **89** as examples of low voltage conducting layers are formed on a front surface of the insulating layer laminated structure **27** (on the interlayer insulating film **30** of the insulating layer **28** that is the uppermost layer).

(87) A protective film **75** and a passivation film **76** as examples of front surface insulating films are laminated successively on an entire surface of the insulating layer laminated structure **27** such as to cover the above integrally. Pad openings **79** and **78** are formed in the films **75** and **76**. The pad openings **79** and **78** expose the high voltage pad layers **88** and the low voltage pad layers **89** as the high voltage pads **14** and the low voltage pads **13**, respectively.

(88) The high voltage pads **14** are arranged in central high voltage regions (HV regions) **36** in which the upper coils **21** are arranged in a plan view of viewing the electronic component **6** from above along a lamination direction of the insulating layer laminated structure **27**.

(89) Here, the high voltage regions **36** include regions of formation of the upper coils **21** and wirings equipotential to the upper coils **21** in the insulating layer **28** embedding the upper coils **21** and peripheral portions of the formation regions.

(90) In this embodiment, a total of four upper coils **21** are formed in pairs of two each at intervals in the length direction of the electronic component **6** as shown in FIG. 3 and FIG. 5. In the inner regions **32** of the upper coils **21** and between the mutually adjacent upper coils **21** of each pair are respectively formed inner coil end wirings **37** and an outer coil end wiring **96**.

(91) With each pair of the upper coils **21**, one upper coil **21** and the other upper coil **21** are electrically connected to each other by the outer coil end wiring **96** in common therebetween. Both

of the upper coils **21**, the outer coil end wiring **96** therebetween, and the inner coil end wirings **37** inside the respective upper coils **21** are all equipotential.

(92) In the insulating layer **28**, the inner regions **32** of the respective upper coils **21** and regions between the upper coils **21** of the respective upper coil **21** pairs are also included in the high voltage regions **36** as being within a range in which electric fields from the upper coils **21**, the inner coil end wirings **37**, and the outer coil end wirings **96** extend.

(93) In each high voltage region **36**, regions overlapping with the respective upper coils **21** in the plan views of FIG. **3** and FIG. **5** and the inner regions **32** of the respective upper coils **21** are examples of high voltage coil formation regions.

(94) In each high voltage region **36**, a region besides the high voltage coil formation regions is a coil exterior region **85** outside the upper coils **21**. The region besides the high voltage coil formation regions includes, for example, a region between the upper coils **21** in each upper coil **21** pair (inter-coil region **50**) and regions along peripheral edges of the respective upper coils **21** (coil periphery regions **99**).

(95) Although being coincident with the high voltage regions **36** in plan view, regions in which the lower coils **20** (low voltage coils) are arranged are separated from the upper coils **21** (high voltage coils) by a plurality of insulating layers **28**. The regions in which the lower coils **20** (low voltage coils) are arranged are not included in the high voltage regions **36** as stated in regard to the present preferred embodiment because effects of the electric fields from the upper coils **21** hardly extend thereto.

(96) As shown in FIG. **3**, a total of six high voltage pads **14** are arranged, one each above the inner region **32** of each upper coil **21** and above the inter-coil region **50** of each upper coil **21** pair.

(97) In classifying the high voltage pads **14** according to the positional configuration thereof, the high voltage pads **14** may include first pads **33** and second pads **34**.

(98) The first pads **33** are arranged above the inner regions **32** of the respective upper coils **21**. Each first pad **33** faces the corresponding inner region **32** in a thickness direction (lamination direction) of the insulating layer laminated structure **27**. The second pads **34** are arranged above the respective inter-coil regions **50**. Each second pad **34** faces the corresponding inter-coil region **50** in a thickness direction (lamination direction) of the insulating layer laminated structure **27**.

(99) As shown in FIG. **3**, FIG. **5**, and FIG. **6**, the first pads **33** are connected through vias **38** to the inner coil end wirings **37** embedded in the same insulating layer **28** as the upper coils **21**.

(100) As shown in FIG. **3**, FIG. **5**, and FIG. **7**, by a similar structure, the second pads **34** are connected through vias **35** to the outer coil end wirings **96** embedded in the same insulating layer **28** as the upper coils **21**.

(101) AC signals transmitted to the upper coils **21** can thereby be output from the high voltage pads **14** via the inner coil end wirings **37** plus the vias **38** and the outer coil end wirings **96** plus the vias **35**.

(102) A combination of an inner coil end wiring **37** and the vias **38** connected thereto and a combination of an outer coil end wiring **96** and the vias **35** connected thereto constitute the high voltage wiring **25** and the high voltage wiring **95**, respectively, of FIG. **2**.

(103) In the insulating layer laminated structure **27**, low voltage regions **46** (FIG. **6** and FIG. **7**), an outer low voltage region **47** (FIG. **3** to FIG. **7**), and an intermediate region **48** (FIG. **3** to FIG. **7**) are set as regions of low potential regions (LV regions) electrically separated from the high voltage regions **36**.

(104) The low voltage regions **46** include regions of formation of the lower coils **20** and wirings equipotential to the lower coils **20** in the insulating layer **28** embedding the lower coils **20** and peripheral portions of the formation regions. As with the relationship between the lower coils **20** and the upper coils **21**, the low voltage regions **46** face the high voltage regions **36** across one layer or more of the insulating layers **28**.

(105) In this embodiment, a total of four lower coils **20** are formed at positions facing the upper

coils **21**, that is, in pairs of two each at intervals in the length direction of the electronic component **6** as shown in FIG. **4**. In the inner regions **31** of the lower coils **20** and between the mutually adjacent lower coils **20** of each pair are respectively formed inner coil end wirings **49** and an outer coil end wiring **97**.

(106) With each pair, one lower coil **20** and the other lower coil **20** are electrically connected to each other by the outer coil end wiring **97** in common therebetween. Both of the lower coils **20**, the outer coil end wiring **97** therebetween, and the inner coil end wirings **49** inside the respective lower coils are all equipotential.

(107) In the insulating layer **28**, the inner regions **31** of the respective lower coils **20** and regions between the lower coils **20** of the respective lower coil **20** pairs are also included in the low voltage regions **46** as being within a range in which electric fields from the lower coils **20**, the inner coil end wirings **49**, and the outer coil end wirings **97** extend. As shown in FIG. **5**, the inner coil end wirings **49** are arranged at positions shifted from the inner coil end wirings **37** at the high voltage side in plan view.

(108) As shown in FIG. **3** to FIG. **5**, the outer low voltage region **47** is set such as to surround the high voltage regions **36** and the low voltage regions **46**. The intermediate region **48** is set between the high voltage regions **36** plus the low voltage regions **46** and the outer low voltage region **47**.

(109) As shown in FIG. **3**, FIG. **6**, and FIG. **7**, the low voltage pads **13** are formed on the front surface of the insulating layer laminated structure **27** (on the interlayer insulating film **30** of the insulating layer **28** that is the uppermost layer) in the outer low voltage region **47**.

(110) As shown in FIG. **6** and FIG. **7**, the outer low voltage region **47** includes a first region **39** as an example of a first space and a second region **40** as an example of a second space.

(111) The first region **39** is a region at one side (left side of sheet surface) across the high voltage pads **14**. The second region **40** is a region at the other side (right side of sheet surface) across the high voltage pads **14**. The low voltage pads **13** are selectively biasedly formed in the first region **39**.

(112) In this embodiment, a total of six low voltage pads **13** are arranged at intervals in the length direction of the electronic component **6** in the first region **39**, one each at the side of the six provided high voltage pads **14**.

(113) The respective low voltage pads **13** are connected to the lower coils **20** by low voltage wirings **24** and **93** routed inside the insulating layer laminated structure **27**. Each low voltage wiring **24** includes a penetrating wiring **51** and a lead-out wiring **52**.

(114) The penetrating wirings **51** are formed in the outer low voltage region **47** in columnar shapes that penetrate from the respective low voltage pads **13** through at least the insulating layer **28** in which the lower coils **20** are formed and reach an insulating layer **28** lower than the lower coils **20**.

(115) More specifically, each penetrating wiring **51** includes low voltage layer wirings **53** and **54** (low voltage wirings) and vias **55**, **56**, and **57**. The low voltage layer wirings **53** and **54** are embedded in island shapes (quadrilateral shapes) in the same insulating layers **28** as the upper coils **21** and the lower coils **20**, respectively.

(116) The plurality of vias **55** connect between the low voltage layer wirings **53** and **54**. The vias **56** connect the low voltage layer wirings **53** at the upper side with the low voltage pads **13**. The vias **57** connect the low voltage layer wirings **54** at the lower side with the lead-out wirings **52**.

(117) The lead-out wirings **52** are formed to line shapes that are led out from the low voltage regions **46** to the outer low voltage region **47** via the insulating layer **28** lower than the lower coils **20**.

(118) More specifically, each lead-out wiring **52** includes the corresponding inner coil end wiring **49**, a lead-out layer wiring **58**, and a via **59**. The lead-out layer wiring **58** is embedded in a line shape in the insulating layer **28** lower than the corresponding lower coil **20**. The lead-out layer wiring **58** crosses below the lower coil **20**.

(119) The via **59** connects the lead-out layer wiring **58** with the inner coil end wiring **49**. The lead-

out layer wiring **58** is connected to the semiconductor substrate **26** via a via **86**. The low voltage wirings **24** are thereby fixed at a substrate voltage (for example, the ground voltage).

(120) Although details shall be omitted, as with the low voltage wirings **24**, the low voltage wirings **93** are also constituted of wirings that include penetrating wirings **43** (FIG. 7) and lead-out wirings **98** (FIG. 3 to FIG. 5).

(121) By the above arrangement, among the plurality of low voltage pads **13**, first pads **41** arranged at the side of the first pads **33** of the high voltage pads **14** are connected via the penetrating wirings **51** and the lead-out wirings **52** to the inner coil end wirings **49** of the lower coils **20** as shown in FIG. 3 to FIG. 6.

(122) As shown in FIG. 3 to FIG. 6, second pads **42** arranged at the side of the second pads **34** of the high voltage pads **14** are connected via the penetrating wirings **43** and the lead-out wirings **98** to the outer coil end wirings **97** of the lower coils **20**. Signals input into the low voltage pads **13** can thereby be transmitted to the lower coils **20** via the penetrating wirings **51** and **43** and the lead-out wirings **52** and **98**.

(123) In the insulating layer laminated structure **27**, a shield layer **69** is formed further outside than the low voltage wirings **24** and **93**. The shield layer **69** prevents entry of moisture into the device from the exterior and spreading of a crack at an end surface into the interior.

(124) As shown in FIG. 3 to FIG. 7, the shield layer **69** is formed to a wall shape along end surfaces of the electronic component **6**. A bottom portion of the shield layer **69** is connected to the semiconductor substrate **26**. The shield layer **69** is thereby fixed at the substrate voltage (for example, the ground voltage).

(125) More specifically, as shown in FIG. 6 and FIG. 7, the shield layer **69** includes shield layer wirings **70** to **72** embedded in the same insulating layers **28** as the upper coils **21**, the lower coils **20**, and the lead-out layer wirings **58**, respectively, a plurality of vias **73** connecting between the wirings, and vias **74** connecting the shielding layer wiring **72** at the lowermost layer and the semiconductor substrate **26**.

(126) Further, on the insulating layer laminated structure **27**, resin films **77** are formed on the protective film **75** and the passivation film **76**. In this embodiment, the resin films **77** are formed selectively on the passivation film **76** such as to integrally cover entireties of the high voltage regions **36**.

(127) That is, the resin films **77** cover the regions overlapping with the respective upper coils **21** in the plan view of FIG. 3, the inner regions **32** of the respective upper coils **21**, the inter-coil regions **50**, and the coil periphery regions **99**. Thereby, in plan view, both the first pads **33** and the second pads **34** of the high voltage pads **14** are covered together with entire peripheries thereof by the resin films **77**.

(128) Openings in the resin films **77** that expose the high voltage pads **14** coincide with the pad openings **79**. The resin films **77** thereby have overlapping portions **44** and **45** riding on peripheral edges of the first pads **33** and the second pads **34** of the high voltage pads **14**.

(129) The protective film **75** is constituted, for example, of SiO₂ and has a thickness of approximately 150 nm. The passivation film **76** is constituted, for example, of SiN and has a thickness of approximately 1000 nm. The resin films **77** are constituted, for example, of polyimide and have a thickness of approximately 4000 nm.

(130) Details of the respective portions of the electronic component **6** shall now be described.

(131) As described with FIG. 2, a large potential difference (for example, of approximately 1200 V) is generated between the lower coils **20** and the upper coils **21** of the electronic component **6**. The insulating layers **28** arranged between the lower coils **20** and the upper coils **21** have a thickness capable of realizing a withstand voltage such that a dielectric breakdown due to the potential difference therebetween would not occur.

(132) Thus, in this embodiment, a plurality of layers (for example, six layers) of the insulating layers **28** are interposed between the coils as shown in FIG. 6. Each insulating layer **28** is

constituted of the laminated structure of the etching stopper film **29** of approximately 300 nm and the interlayer insulating film **30** of approximately 2100 nm. By making a total thickness **L2** of the insulating layers **28** be not less than 12.0 μm and not more than 16.8 μm , DC insulation in a vertical direction is realized between the lower coils **20** and the upper coils **21**.

(133) A distance **L1** between the high voltage pads **14** and the low voltage pads **13** is greater in comparison to the total thickness **L2** of the insulating layers **28** between the lower coils and the upper coils **21**. For example, the distance **L1** is generally not less than 100 μm and not more than 450 μm and, expressed as a ratio with respect to the thickness **L2** (distance **L1**/thickness **L2**), is not less than 6/1 and not more than 40/1.

(134) FIG. **8** is a sectional view of the arrangement of an electronic component **6** according to a comparative mode of the present invention. FIG. **9** is a sectional view taken along line IX-IX in FIG. **8**. As shown in FIG. **8** and FIG. **9**, with the electronic component **6** according to the comparative example, the resin films **77** expose peripheries of the second pads **34** of the high voltage pads **14**.

(135) FIG. **10** is a graph comparing an average dielectric breakdown voltage of the electronic component according to the comparative mode of the present invention and an average dielectric breakdown voltage of the electronic component **6** according to the first preferred embodiment of the present invention. In FIG. **10**, the ordinate represents the average dielectric breakdown voltage [kVrms].

(136) Referring to FIG. **10**, the average dielectric breakdown voltage of the electronic component **6** according to the first preferred embodiment was increased by 7.5% with respect to the average dielectric breakdown voltage of the electronic component **6** according to the comparative mode. From this, it was found that the average dielectric breakdown voltage can be improved by covering the peripheries of the second pads **34** by the resin films **77**.

(137) FIG. **11** is a graph comparing a variation of dielectric breakdown voltage of the electronic component **6** according to the comparative mode of the present invention and a variation of dielectric breakdown voltage of the electronic component **6** according to the first preferred embodiment of the present invention. In FIG. **11**, the ordinate represents the variation of the average dielectric breakdown voltage.

(138) Referring to FIG. **11**, the variation of dielectric breakdown voltage of the electronic component **6** according to the first preferred embodiment was decreased by 27.9% with respect to the variation of dielectric breakdown voltage of the electronic component **6** according to the comparative mode. From this, it was found that the variation of dielectric breakdown voltage can be suppressed by covering the peripheries of the second pads **34** by the resin films **77**.

(139) FIG. **12** is a diagram for describing the planar structure of upper coils **21** of an electronic component **101** according to a second preferred embodiment of the present invention. With this embodiment, structures corresponding to structures of the electronic component **6** are provided with the same reference symbols and description thereof is omitted.

(140) With an electronic component with which a low voltage portion and a high voltage portion are laid out on the same plane or on planes that can be deemed to be substantially the same (hereinafter referred to simply as “on the plane in common”), the high voltage portion forms an electric field with the low voltage portion. Therefore, a comparatively high electric field tends to concentrate on the high voltage portion.

(141) For example, with an electronic component with which a single transformer is arranged by a low voltage coil and a high voltage coil that face each other, the high voltage coil forms an electric field with the low voltage coil. Therefore, a comparatively high electric field tends to concentrate on the high voltage coil. Occurrence of such concentration of electric field can be a detriment in terms of improving withstand voltage.

(142) Thus, with this embodiment, an electronic component that enables relaxation of such concentration of electric field and improvement of the withstand voltage is provided.

(143) In the following, out of the first transformer **301** and the second transformer **302**, the structure at the first transformer **301** side shall be described as an example. The structure at the second transformer **302** side is the same as the structure at the first transformer **301** side and therefore the same reference symbols are provided and description thereof is omitted.

(144) Also in the following, for convenience of description, one of the upper coils **21** out of the two upper coils **21** shall be referred to as the first upper coil **21A** and the other upper coil **21** shall be referred to as the second upper coil **21B** as necessary. When mention is made simply of the upper coils **21A** and **21B**, it shall be deemed that both the first upper coil **21A** and the second upper coil **21B** are included.

(145) Also in the following, a direction in which the first upper coil **21A** and the second upper coil **21B** face each other shall be referred to as the “first direction A” and an intersecting direction intersecting the first direction A shall be referred to as the “second direction B.” More specifically, the second direction B is an orthogonal direction orthogonal to the first direction A.

(146) Referring to FIG. **12**, the electronic component **101** is, in this embodiment, a transformer chip that includes transformers. The electronic component **101** includes withstand voltage enhancement structures **102** having conductive property. Each withstand voltage enhancement structure **102** is formed in a region between members of a low voltage side and members of a high voltage side. The members of the low voltage side include, for example, the low voltage pads **13**, the shield layer **69**, etc., that are fixed at a reference potential or a ground potential.

(147) The members of the high voltage side include, for example, the high voltage pads **14**, the upper coils **21A** and **21B**, etc. The withstand voltage enhancement structure **102** suppresses withstand voltage degradation due to electric fields that are formed in the region between the members of the low voltage side and the members of the high voltage side.

(148) More specifically, the withstand voltage enhancement structure **102** includes a first withstand voltage enhancement structure **103** of the high voltage side and a second withstand voltage enhancement structure **104** of the low voltage side. In FIG. **12**, each first withstand voltage enhancement structure **103** and each second withstand voltage enhancement structure **104** are shown in simplified manner.

(149) The first withstand voltage enhancement structure **103** is formed along the upper coils **21A** and **21B**. The first withstand voltage enhancement structure **103** surrounds the upper coils **21A** and **21B** such as to demarcate the upper coils **21A** and **21B** from other regions.

(150) More specifically, the first withstand voltage enhancement structure **103** surrounds the upper coils **21A** and **21B** and the outer coil end wiring **96** formed between the upper coils **21A** and **21B** altogether. That is, the first withstand voltage enhancement structure **103** is formed to a ring shape (elliptical ring shape) in plan view.

(151) The second withstand voltage enhancement structure **104** is formed in a region between the upper coils **21A** and **21B** and the low voltage layer wirings **53** (low voltage pads **13**) in plan view. The second withstand voltage enhancement structure **104** extends in a line shape along the first direction A.

(152) The second withstand voltage enhancement structure **104** is formed along the plurality of low voltage layer wirings **53** (low voltage pads **13**) in plan view. The second withstand voltage enhancement structure **104** thereby protrudes further outside than outer contours of the low voltage pads **13** in plan view.

(153) The second withstand voltage enhancement structure **104** extends in the line shape along the first direction A such as to pass along the plurality of low voltage pads **13**. The second withstand voltage enhancement structure **104** thereby demarcates the plurality of low voltage pads **13** (low voltage layer wirings **53**) respectively from the upper coils **21A** and **21B**.

(154) The structure of the withstand voltage enhancement structure **102** shall now be described more specifically with reference to FIG. **13** to FIG. **17**. FIG. **13** is an enlarged view of a region XIII shown in FIG. **12**. FIG. **14** is an enlarged view of a region XIV shown in FIG. **13**. FIG. **15** is an

enlarged view of a region XV shown in FIG. 13. FIG. 16 is a sectional view taken along line XVI-XVI shown in FIG. 12. FIG. 17 is a sectional view taken along line XVII-XVII shown in FIG. 12. (155) In FIG. 13, outer contours of the upper coils **21A** and **21B** are indicated by thick lines for convenience of description. The outer contours of the upper coils **21A** and **21B** are respectively formed by outer peripheral edges of spiral patterns **105** of one turn each that form outermost peripheries of the upper coils **21A** and **21B**.

(156) In FIG. 14, an outer contour of a lower coil **20** is indicated by a broken line for convenience of description. The outer contour of the lower coil **20** is formed by an outer peripheral edge of a spiral pattern of one turn that forms an outermost periphery of the lower coil **20**. Also, in FIG. 14, the first pad **33** and the second pad **34** of a high voltage pad **14** are respectively indicated by broken lines for convenience of description.

(157) Referring to FIG. 13 and FIG. 14, the upper coils **21A** and **21B** each include the corresponding inner coil end **22**, outer coil end **94**, and a spiral pattern **105**.

(158) The inner coil ends **22** of the upper coils **21A** and **21B** are respectively formed inside regions surrounded by outer contours of lower coils **20** in plan view. The outer coil ends **94** of the upper coils **21A** and **21B** are respectively formed in regions outside the regions surrounded by the outer contours of the lower coils **20** in plan view. The spiral patterns **105** of the upper coils **21A** and **21B** are respectively wound outwardly from the inner coil ends **22** toward the outer coil ends **94**.

(159) The number of turns of the spiral pattern **105** may be not less than 5 and not more than 30 (for example, 15). A width of each spiral pattern **105** may be not less than 0.5 μm and not more than 5 μm . The width of the spiral pattern **105** is preferably not less than 1 μm and not more than 3 μm . The width of the spiral pattern **105** is defined by a width in a direction orthogonal to a spiraling direction.

(160) A winding pitch PTL of the spiral pattern **105** may be not less than 0.1 μm and not more than 10 μm . The winding pitch PTL of the spiral pattern **105** is preferably not less than 1 μm and not more than 3 μm . The winding pitch PTL of the spiral pattern **105** is defined by a distance between two spiral patterns **105** that are mutually adjacent in the direction orthogonal to the spiraling direction.

(161) The inner coil ends **22** of the upper coils **21A** and **21B** are respectively connected to the inner coil end wirings **37** via inner connection portions **106**. The inner connection portions **106** are respectively led out from the inner coil end wirings **37** toward the inner coil ends **22**.

(162) The outer coil ends **94** of the upper coils **21A** and **21B** are respectively connected to the outer coil end wiring **96** via outer connection portions **107**. The outer connection portions **107** are respectively led out from the outer coil end wiring **96** toward the outer coil ends **94**.

(163) As described with the first preferred embodiment, the structure of the lower coils **20** is substantially the same as the structure of the upper coils **21A** and **21B**. Specific description of the lower coils **20** is omitted.

(164) Referring to FIG. 13, FIG. 14, and FIG. 17, the first withstand voltage enhancement structure **103** is formed inside the same insulating layer **28** (interlayer insulating film **30**) as the upper coils **21A** and **21B**. The first withstand voltage enhancement structure **103** is formed through a process in common with the upper coils **21A** and **21B**. The first withstand voltage enhancement structure **103** is thus formed by an electrode layer in common with the upper coils **21A** and **21B**.

(165) The first withstand voltage enhancement structure **103** is formed along the outer contours of the upper coils **21A** and **21B** such as to protrude further outward than the outer contours of the lower coils **20** in plan view (see the broken line in FIG. 14). Further, the first withstand voltage enhancement structure **103** is formed along outer contours of the second pads **34** such as to protrude further outward than the outer contours of the second pad **34** in plan view (see the broken lines in FIG. 14).

(166) The first withstand voltage enhancement structure **103** surrounds the upper coils **21A** and **21B** and the outer coil end wiring **96** formed between the upper coils **21A** and **21B** altogether. That

is, the first withstand voltage enhancement structure **103** is formed to the ring shape (elliptical ring shape) in plan view. The first withstand voltage enhancement structure **103** demarcates the upper coils **21A** and **21B** and the outer coil end wiring **96** formed between the upper coils **21A** and **21B** from other regions.

(167) More specifically, the first withstand voltage enhancement structure **103** includes a first dummy conductor pattern group **109** formed by an assembly of a plurality (for example, six) of first dummy conductor patterns **108**. In FIG. **16** and FIG. **17**, portions of the first dummy conductor pattern group **109** are omitted from illustration. Each of the plurality of first dummy conductor patterns **108** has a discontinuous pattern with respect to the spiral patterns **105** of the upper coils **21A** and **21B**.

(168) The plurality of first dummy conductor patterns **108** are formed at intervals along directions away from the upper coils **21A** and **21B**. Each first dummy conductor pattern **108** surrounds the upper coils **21A** and **21B** and the outer coil end wiring **96** formed between the upper coils **21A** and **21B** altogether. That is, each first dummy conductor pattern **108** is formed to a ring shape (elliptical ring shape) in plan view.

(169) A width of the first dummy conductor pattern **108** may be not less than $0.5\ \mu\text{m}$ and not more than $5\ \mu\text{m}$. The width of the first dummy conductor pattern **108** is preferably not less than $1\ \mu\text{m}$ and not more than $3\ \mu\text{m}$. The width of the first dummy conductor pattern **108** may be equal to the width of each spiral pattern **105**. The width of the first dummy conductor pattern **108** is defined by a width in a direction orthogonal to a direction in which the first dummy conductor pattern **108** extends.

(170) In this embodiment, each first dummy conductor pattern **108** includes an open portion **110** at which an electrode layer is not present. The open portion **110** of each first dummy conductor pattern **108** is formed by a portion of the insulating layer **28** (interlayer insulating film **30**). Each first dummy conductor pattern **108** is thereby formed to a shape with ends.

(171) The first dummy conductor pattern group **109** includes an inside first dummy conductor pattern **108** positioned at the upper coils **21A** and **21B** side and an outside first dummy conductor pattern **108** positioned at an opposite side from the upper coils **21A** and **21B** with respect to the inside first dummy conductor pattern **108**.

(172) The outside first dummy conductor pattern **108** extends such as to block the open portion **110** of the inside first dummy conductor pattern **108** from the outside. The open portion **110** of the outside first dummy conductor pattern **108** is formed in a region differing from the open portion **110** of the inside first dummy conductor pattern **108**.

(173) By the open portions **110**, open circuits that include the first dummy conductor patterns **108** are formed. That is, the open portions **110** prevent a current path from forming in the first dummy conductor patterns **108**.

(174) Generation of noise due to the first dummy conductor patterns **108** is thereby suppressed. Obviously, at least one or all of the plurality of first dummy conductor patterns **108** may be of endless shape instead.

(175) The respective first dummy conductor patterns **108** are connected to the outer coil end wiring **96** via a first dummy connection portion **111**. The respective first dummy conductor patterns **108** are thereby fixed to be equipotential to the outer coil ends **94** of the upper coils **21A** and **21B**.

(176) The first dummy connection portion **111** is led out along an arbitrary direction from the outer coil end wiring **96**. The first dummy connection portion **111** may be led out from a region differing from the outer connection portions **107**. In this embodiment, the first dummy connection portion **111** is led out along the second direction B from a region differing from the outer connection portions **107**.

(177) The first withstand voltage enhancement structure **103** includes a first proximal region **112**, a second proximal region **113**, a first connection region **114**, and a second connection region **115**. The first proximal region **112**, the second proximal region **113**, the first connection region **114**, and the

second connection region **115** are respectively formed by the first dummy conductor pattern group **109**.

(178) The first proximal region **112** is proximal to the first upper coil **21A** and extends in a U shape along the outer contour of the first upper coil **21A**. The first proximal region **112** sandwiches the first upper coil **21A** from three directions. The first proximal region **112** demarcates the first upper coil **21A** from the low voltage pads **13** (low voltage layer wirings **53**) and the shield layer **69**.

(179) The second proximal region **113** is proximal to the second upper coil **21B** and extends in a U shape along the outer contour of the second upper coil **21B**. The second proximal region **113** sandwiches the second upper coil **21B** from three directions. The second proximal region **113** demarcates the second upper coil **21B** from the low voltage pads **13** (low voltage layer wirings **53**) and the shield layer **69**.

(180) The first connection region **114** is formed in a line shape extending along the first direction A in a region at the low voltage pad **13** side with respect to the outer coil end wiring **96**. The first connection region **114** connects one end of the first proximal region **112** and one end of the second proximal region **113**. The first connection region **114** demarcates portions of the upper coils **21A** and **21B** and the outer coil end wiring **96** from the low voltage pads **13** (low voltage layer wirings **53**).

(181) More specifically, the first connection region **114** is formed along the outer contours of the second pads **34** (see the broken lines in FIG. **14**) in the region at the low voltage pad **13** side with respect to the outer coil end wiring **96**.

(182) The plurality of first dummy conductor patterns **108** included in the first connection region **114** are formed at intervals along a direction away from the second pads **34**. The direction away from the second pads **34** is the second direction B.

(183) The second connection region **115** is formed in a line shape extending along the first direction A in a region at an opposite side from the first connection region **114** with respect to the outer coil end wiring **96**. The second connection region **115** connects the other end of the first proximal region **112** and the other end of the second proximal region **113**. The second connection region **115** demarcates portions of the upper coils **21A** and **21B** and the outer coil end wiring **96** from the shield layer **69**.

(184) More specifically, the second connection region **115** is formed along the outer contours of the second pads **34** (see the broken lines in FIG. **14**) in the region at the opposite side from the first connection region **114** with respect to the outer coil end wiring **96**.

(185) The plurality of first dummy conductor patterns **108** included in the second connection region **115** are formed at intervals along a direction away from the second pads **34**. The direction away from the second pads **34** is the second direction B.

(186) The plurality of first dummy conductor patterns **108** included in the first proximal region **112** and the second proximal region **113** are respectively formed at a first pitch **PT1**. The first pitch **PT1** of the first dummy conductor patterns **108** may be equal to the winding pitch **PTL** of the spiral pattern **105** (**PT1=PTL**).

(187) The first pitch **PT1** is defined by a distance between the first dummy conductor pattern **108** most proximal to the upper coils **21A** and **21B** and the upper coils **21A** and **21B** and a distance between two first dummy conductor patterns **108** that are mutually adjacent.

(188) The plurality of first dummy conductor patterns **108** included in the first connection region **114** and the second connection region **115** are formed at second pitches **PTa**, **PTb**, **PTc**, **PTd**, **PTe**, and **PTf**, respectively.

(189) The second pitch **PTa** is defined by a distance along the second direction B between the first dummy conductor pattern **108** most proximal to the second pads **34** and the second pads **34**. The second pitches **PTb** to **PTf** are each defined by a distance along the second direction B of two first dummy conductor patterns **108** that are mutually adjacent.

(190) The second pitches **PTa** to **PTf** can each take on values different from the first pitch **PT1** (**PTa**

to PTf≠PT1). The second pitches PTa to PTf may be not less than 1 μm and not more than 50 μm. The second pitches PTa to PTf can take on various values in a range of not less than 1 μm to not more than 50 μm. The respective values of the second pitches PTa to PTf shall be described in detail later.

(191) In the first proximal region **112** and the second proximal region **113**, a protrusion amount **Z1** of the first withstand voltage enhancement structure **103** with respect to the outer contours of the lower coils **20** may exceed 0 μm and be not more than 100 μm ($0\ \mu\text{m} < Z1 \leq 100\ \mu\text{m}$). The protrusion amount **Z1** may be adjusted by changing the number of the first dummy conductor patterns **108** and the value of the first pitch **PT1** thereof.

(192) One configuration example where the electronic component **101** has a withstand voltage of not less than 5000 V is as follows. The insulating layers **28** may have a dielectric breakdown strength of not less than 8 MV/cm and not more than MV/cm.

(193) The insulating layer **28** may include at least one of either of SiO.sub.2 and SiN. In this case, the protrusion amount **Z1** is preferably not less than 10 μm. More specifically, the protrusion amount **Z1** is more preferably not less than 20 μm.

(194) The protrusion amount **Z1** is defined by a distance, in the first proximal region **112** and the second proximal region **113**, between the outer contours of the lower coils **20** and an outer peripheral edge of the first dummy conductor pattern **108** forming an outermost periphery of the first withstand voltage enhancement structure **103**.

(195) The resin package **2** may have a dielectric breakdown strength of not less than 0.1 and not more than 0.3 MV/cm. The resin package **2** may include at least one molded resin among an epoxy resin, a polyimide resin, and a polybenzoxazole resin. The “dielectric breakdown strength” is defined by the maximum value of electric field strength that can be applied without causing dielectric breakdown (the same applies hereinafter).

(196) The first proximal region **112** of the first withstand voltage enhancement structure **103** forms a first coil side withstand voltage enhancement structure **116** that suppresses decrease in withstand voltage at the first upper coil **21A** side. More specifically, the first coil side withstand voltage enhancement structure **116** suppresses the decrease in withstand voltage due to an electric field that is formed between the first upper coil **21A** and the low voltage pads **13** (low voltage layer wirings **53**). Also, the first coil side withstand voltage enhancement structure **116** suppresses the decrease in withstand voltage due to an electric field that is formed between the first upper coil **21A** and the shield layer **69**.

(197) The second proximal region **113** of the first withstand voltage enhancement structure **103** forms a second coil side withstand voltage enhancement structure **117** that suppresses decrease in withstand voltage at the second upper coil **21B** side. More specifically, the second coil side withstand voltage enhancement structure **117** suppresses the decrease in withstand voltage due to an electric field that is formed between the second upper coil **21B** and the low voltage pads **13** (low voltage layer wirings **53**). Also, the second coil side withstand voltage enhancement structure **117** suppresses the decrease in withstand voltage due to an electric field that is formed between the second upper coil **21B** and the shield layer **69**.

(198) The first connection region **114** of the first withstand voltage enhancement structure **103** forms a first pad side withstand voltage enhancement structure **118** that suppresses decrease in withstand voltage at the second pad **34** side. More specifically, the first pad side withstand voltage enhancement structure **118** suppresses the decrease in withstand voltage due to an electric field that is formed between the outer coil end wiring **96** and the low voltage pads **13** (low voltage layer wirings **53**). Also, the first pad side withstand voltage enhancement structure **118** suppresses the decrease in withstand voltage due to an electric field that is formed between the second pads **34** and the shield layer **69**.

(199) The second connection region **115** of the first withstand voltage enhancement structure **103** forms a second pad side withstand voltage enhancement structure **119** that suppresses decrease in

withstand voltage at the second pad **34** side. More specifically, the second pad side withstand voltage enhancement structure **119** suppresses the decrease in withstand voltage due to the electric field that is formed between the second pads **34** and the shield layer **69**.

(200) Referring to FIG. **13**, FIG. **15**, and FIG. **17**, the second withstand voltage enhancement structure **104** is formed inside the same insulating layer **28** (interlayer insulating film **30**) as the upper coils **21A** and **21B**. The second withstand voltage enhancement structure **104** is formed through a process in common with the upper coils **21A** and **21B**. The second withstand voltage enhancement structure **104** is thus formed by the electrode layer in common with the upper coils **21A** and **21B**.

(201) The second withstand voltage enhancement structure **104** includes a second dummy conductor pattern group **122** formed by an assembly of a plurality (for example, three) of second dummy conductor patterns **121**. In FIG. **16** and FIG. **17**, portions of the second dummy conductor pattern group **122** are omitted from illustration. Each of the plurality of second dummy conductor patterns **121** has a discontinuous pattern with respect to the spiral patterns **105** of the upper coils **21A** and **21B**.

(202) Each of the plurality of second dummy conductor patterns **121** includes a line shaped pattern that extends in the first direction A. The plurality of second dummy conductor patterns **121** are aligned at intervals from each other along the second direction B.

(203) A width of each second dummy conductor pattern **121** may be not less than $0.5\ \mu\text{m}$ and not more than $5\ \mu\text{m}$. The width of the second dummy conductor pattern **121** is preferably not less than $1\ \mu\text{m}$ and not more than $3\ \mu\text{m}$. The width of the second dummy conductor pattern **121** may be equal to the width of each spiral pattern **105**.

(204) The width of the second dummy conductor pattern **121** may be equal to the width of each first dummy conductor pattern **108**. The width of the second dummy conductor pattern **121** is defined by a width in a direction orthogonal to a direction in which the second dummy conductor pattern **121** extends. The direction orthogonal to the direction in which the second dummy conductor pattern **121** extends is the second direction B.

(205) The plurality of second dummy conductor patterns **121** are respectively formed at a third pitch **PT3**. The third pitch **PT3** may be equal to the winding pitch **PTL** of the spiral pattern **105** (**PT3=PTL**).

(206) The third pitch **PT3** is defined by a distance between the second dummy conductor pattern **121** most proximal to the low voltage pads **13** and the low voltage pads **13** and a distance between two second dummy conductor patterns **121** that are mutually adjacent.

(207) Each second dummy conductor pattern **121** is formed to a shape with ends. Open circuits that include the second dummy conductor patterns **121** are thereby formed. That is, the open circuits prevent a current path from forming in the second dummy conductor patterns **121**.

(208) Generation of noise due to the second dummy conductor patterns **121** is thereby suppressed. Obviously, at least one or all of the plurality of second dummy conductor patterns **121** may be of endless shape instead.

(209) The respective second dummy conductor patterns **121** are connected to a low voltage layer wiring **53** via a second dummy connection portion **123**. The respective second dummy conductor patterns **121** are thereby fixed to be equipotential to the low voltage pads **13** (low voltage layer wirings **53**).

(210) The second dummy connection portion **123** is led out from an arbitrary low voltage layer wiring **53** toward a region at the upper coils **21A** and **21B** side. In this embodiment, the second dummy connection portion **123** is led out from the low voltage layer wiring **53** corresponding to the outer coil end wiring **97** of the lower coils **20**.

(211) In this embodiment, the second dummy connection portion **123** is led out in a line shape along the second direction B. One or a plurality of the second dummy connection portion **123** may be led out from one or a plurality of the low voltage layer wiring **53**.

(212) A protrusion amount **Z2** of the second withstand voltage enhancement structure **104** may exceed 0 μm and be not more than 50 μm ($0\ \mu\text{m} < \text{Z2} \leq 50\ \mu\text{m}$). The protrusion amount **Z2** of the second withstand voltage enhancement structure **104** is defined by a distance in the second direction **B** between the outer contours of the low voltage pads **13** and a peripheral edge at the upper coils **21A** and **21B** side of the second dummy conductor pattern **121** most proximal to the upper coils **21A** and **21B**.

(213) The second withstand voltage enhancement structure **104** suppresses the decrease in withstand voltage due to the electric field that is formed between the first upper coil **21A** and the low voltage pads **13** (low voltage layer wirings **53**). Also, the second withstand voltage enhancement structure **104** suppresses the decrease in withstand voltage due to the electric field that is formed between the second upper coil **21B** and the low voltage pads **13** (low voltage layer wirings **53**). Also, the second withstand voltage enhancement structure **104** suppresses decrease in withstand voltage due to an electric field that is formed between the second pads **34** and the low voltage pads **13** (low voltage layer wirings **53**).

(214) Next, a relationship between the withstand voltage enhancement structure **102** and electric field strength and a relationship between the withstand voltage enhancement structure **102** and dielectric breakdown resistance shall be described specifically. It shall be deemed that the electric field strength includes a peak value of the electric field strength.

(215) Although in the following, a description shall be provided with the first coil side withstand voltage enhancement structure **116** as an example, the same description also holds for the second coil side withstand voltage enhancement structure **117**. It is therefore deemed that the description related to the first coil side withstand voltage enhancement structure **116** applies to a description related to the second coil side withstand voltage enhancement structure **117** and the description related to the second coil side withstand voltage enhancement structure **117** is omitted.

(216) Also, although in the following, a description shall be provided with the first pad side withstand voltage enhancement structure **118** as an example, the same description also holds for the second pad side withstand voltage enhancement structure **119**. It is therefore deemed that the description related to the first pad side withstand voltage enhancement structure **118** applies to a description related to the second pad side withstand voltage enhancement structure **119** and the description related to the second pad side withstand voltage enhancement structure **119** is omitted.

(217) To examine a relationship between the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** and the electric field strength in the first coil side withstand voltage enhancement structure **116**, six samples A1, B1, C1, D1, E1, and F1 were prepared as indicated in Table 1 below.

(218) TABLE-US-00001 TABLE 1 Sample A1 B1 C1 D1 E1 F1 Protrusion 0 μm 10 μm 20 μm 30 μm 40 μm 50 μm amount **Z1**

(219) Sample A1 is an electronic component according to a reference example. The electronic component according to the reference example has the same structure as the electronic component **101** according to the present preferred embodiment with the exception of not including the withstand voltage enhancement structure **102**. Description is omitted in regard to the structure of the electronic component according to the reference example (the same applies hereinafter).

(220) Sample B1 is the electronic component **101** with which the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is set to 10 μm . Sample C1 is the electronic component **101** with which the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is set to 20 μm .

(221) Sample D1 is the electronic component **101** with which the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is set to 30 μm . Sample E1 is the electronic component **101** with which the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is set to 40 μm . Sample F1 is the electronic component **101** with which the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is set to 50 μm .

(222) FIG. **18** is a graph of a relationship between the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** and the electric field strength determined by simulation. In FIG. **18**, the ordinate represents the electric field strength [kV/ram] and the abscissa represents a distance [μm] between the first withstand voltage enhancement structure **103** and the shield layer **69**.

(223) In the following, outer contours (outermost peripheral edges) of the upper coils **21A** and **21B** shall be referred to simply as the “upper coil ends.” Also, an outer contour (outermost peripheral edge) of the first withstand voltage enhancement structure **103** shall be referred to simply as the “first withstand voltage enhancement structure end.” Also, an inner contour (inner peripheral edge) of the shield layer **69** shall be referred to simply as the “shield layer end.”

(224) In FIG. **18**, a first curve LN1, a second curve LN2, a third curve LN3, a fourth curve LN4, a fifth curve LN5, and a sixth curve LN6 are shown.

(225) The first curve LN1 represents the simulation results for sample A1. The second curve LN2 represents the simulation results for sample B1. The third curve LN3 represents the simulation results for sample C1.

(226) The fourth curve LN4 represents the simulation results for sample D1. The fifth curve LN5 represents the simulation results for sample E1. The sixth curve LN6 represents the simulation results for sample F1.

(227) Referring to the first curve LN1, the electric field strength at the upper coil ends side of sample A1 was 56 kV/mm. Referring to the second curve LN2, the electric field strength at the first withstand voltage enhancement structure end of sample B1 was 34 kV/ram. Referring to the third curve LN3, the electric field strength at the first withstand voltage enhancement structure end of sample C1 was 28 kV/ram.

(228) Referring to the fourth curve LN4, the electric field strength at the first withstand voltage enhancement structure end of sample D1 was 28 kV/mm. Referring to the fifth curve LN5, the electric field strength at the first withstand voltage enhancement structure end of sample E1 was 28 kV/ram. Referring to the sixth curve LN6, the electric field strength at the first withstand voltage enhancement structure end of sample F1 was 28 kV/ram.

(229) The electric field strength at the upper coil ends of sample A1 was thus higher than the electric field strengths of samples B1 to F1. That is, with sample A1 that does not have the first withstand voltage enhancement structure **103**, the concentration of electric field on the upper coil ends was significant. On the other hand, it was found that the concentration of electric field on the upper coil ends is relaxed with samples B1 to F1 each having the first withstand voltage enhancement structure **103**.

(230) Referring to the first curve LN1, the electric field strength at the shield layer end of sample A1 was 20 kV/ram. Referring to the second curve LN2, the electric field strength at the shield layer end of sample B1 was 24 kV/ram. Referring to the third curve LN3, the electric field strength at the shield layer end of sample C1 was 26 kV/ram.

(231) Referring to the fourth curve LN4, the electric field strength at the shield layer end of sample D1 was 28 kV/mm. Referring to the fifth curve LN5, the electric field strength at the shield layer end of sample E1 was 29 kV/mm. Referring to the sixth curve LN6, the electric field strength at the shield layer end of sample F1 was 30 kV/mm.

(232) The electric field strength at the shield layer end increased such as to be proportional to the increase in the protrusion amount **Z1** of the first withstand voltage enhancement structure **103**. These results are in accordance with the physical law that electric field is inversely proportional to distance.

(233) As described above, from the first curve LN1 to the sixth curve LN6, it was found that the concentration of electric field on the upper coil ends is relaxed as long as the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is not set to zero (that is, as long as the protrusion amount $\text{Z1} > 0$). On the other hand, when the protrusion amount **Z1** of the first withstand

voltage enhancement structure **103** exceeds μm , the electric field strength at the first withstand voltage enhancement structure end converged to approximately 28 kV/mm.

(234) That is, it was found that when the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** exceeds a certain value (20 μm in the present case), the electric field strength at the first withstand voltage enhancement structure **103** side is determined by a distance between the first withstand voltage enhancement structure end and the shield layer end. This is also one of the reasons why the electric field strength at the shield layer end increased.

(235) The results of FIG. **18** are summarized as follows. It is preferable to provide the first withstand voltage enhancement structure **103** (first coil side withstand voltage enhancement structure **116**). Trailing ends of the electric fields that are formed between the upper coils **21A** and **21B** and the lower coils **20** can thereby be shifted from the upper coils **21A** and **21B** side to the first withstand voltage enhancement structure **103** side.

(236) Also, the first withstand voltage enhancement structure **103** protrudes outward from the outer contours of the upper coils **21A** and **21B**. The electric fields that are formed between the lower coils **20** and the upper coils **21A** and **21B** can thus be shielded by the first withstand voltage enhancement structure **103**. The electric field can thereby be suppressed from forming such as to wrap around end portions of the upper coils **21A** and **21B**.

(237) Consequently, the concentration of electric field on the upper coils **21A** and **21B** can be relaxed. More specifically, the concentration of electric field on the upper coil ends (first withstand voltage enhancement structure end) can be relaxed in the region between the upper coils **21A** and **21B** and the low voltage pads **13**. Also, the concentration of electric field on the upper coil ends (first withstand voltage enhancement structure end) can be relaxed in the region between the upper coils **21A** and **21B** and the shield layer **69**.

(238) Preferably, the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** exceeds 0 μm . That “the protrusion amount **Z1** exceeds 0 μm ” means that a first dummy conductor pattern **108** is formed.

(239) The protrusion amount **Z1** of the first withstand voltage enhancement structure **103** may be not less than 10 μm and not more than 50 μm . In this case, the electric field strength at the first withstand voltage enhancement structure end becomes not more than 34 kV/mm and the concentration of electric field on the upper coil ends can be relaxed. Also, in this case, an absolute value of a difference between the electric field strength at the first withstand voltage enhancement structure end and the electric field strength at the shield layer end becomes not more than 15 kV/mm.

(240) The protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is preferably not less than 20 μm and not more than 50 μm . In this case, the electric field strength at the first withstand voltage enhancement structure end becomes not more than 30 kV/mm and the concentration of electric field on the upper coil ends can be relaxed. Also, in this case, the absolute value of the difference between the electric field strength at the first withstand voltage enhancement structure end and the electric field strength at the shield layer end becomes not more than 5 kV/mm.

(241) To examine a relationship between the second withstand voltage enhancement structure **104** and the electric field strength, four samples A2, B2, C2, and D2 were prepared as indicated in Table 2 below.

(242) TABLE-US-00002 TABLE 2 Sample A2 B2 C2 D2 Number of second 0 pcs 3 pcs 6 pcs 12 pcs dummy patterns 121

(243) Sample A2 is the electronic component according to the reference example. Sample B2 is the electronic component **101** that includes three second dummy conductor patterns **121**. Sample C2 is the electronic component **101** that includes six second dummy conductor patterns **121**. Sample D2 is the electronic component **101** that includes twelve second dummy conductor patterns **121**.

(244) FIG. **19** is a graph of a relationship between the number of the second dummy conductor

patterns **121** and the electric field strength determined by simulation. In FIG. **19**, the ordinate represents the electric field strength [kV/ram] and the abscissa represents the number [pcs] of the second dummy conductor patterns **121**.

(245) In the following, peripheral edges of the low voltage pads **13** at the upper coils **21A** and **21B** side shall be referred to simply as the “low voltage pad ends.” Also, a peripheral edge of the second withstand voltage enhancement structure **104** at the upper coils **21A** and **21B** side shall be referred to simply as the “second withstand voltage enhancement structure end.”

(246) In FIG. **19**, a first plotted point **P1**, a second plotted point **P2**, a third plotted point **P3**, and a fourth plotted point **P4** are indicated.

(247) The first plotted point **P1** represents the electric field strength at the low voltage pad ends in sample A2. The second plotted point **P2** represents the electric field strength at the second withstand voltage enhancement structure end in sample B2.

(248) The third plotted point **P3** represents the electric field strength at the second withstand voltage enhancement structure end in sample C2. The fourth plotted point **P4** represents the electric field strength at the second withstand voltage enhancement structure end in sample D2.

(249) Referring to the first plotted point **P1**, the electric field strength at the low voltage pad ends in sample A2 was 45 kV/ram. Referring to the second plotted point **P2**, the electric field strength at the second withstand voltage enhancement structure end in sample B2 was 30 kV/ram.

(250) Referring to the third plotted point **P3**, the electric field strength at the second withstand voltage enhancement structure end in sample C2 was 35 kV/mm. Referring to the fourth plotted point **P4**, the electric field strength at the second withstand voltage enhancement structure end in sample D2 was 38 kV/ram.

(251) The electric field strength at the low voltage pad ends of sample A2 was thus higher than the electric field strengths at the second withstand voltage enhancement structure ends of samples B2 to D2. That is, with sample A2 that does not have the second withstand voltage enhancement structure end, the concentration of electric field on the low voltage pad ends was significant. On the other hand, it was found that the concentration of electric field on the low voltage pad ends is relaxed with samples B2 to D2 each having the second withstand voltage enhancement structure end.

(252) Although unillustrated, in sample B2, the electric field strength at the upper coil ends was 25 kV/ram. Although unillustrated, in sample C2, the electric field strength at the upper coil ends was 30 kV/ram. Although unillustrated, in sample D2, the electric field strength at the upper coil ends was 31 kV/ram.

(253) The electric field strength at the upper coil end increased such as to be proportional to the increase in the number of the second dummy conductor patterns **121**. These results are in accordance with the physical law that electric field is inversely proportional to distance.

(254) As described above, it was found that the concentration of electric field on the low voltage pads **13** is relaxed by forming the second withstand voltage enhancement structure **104**. On the other hand, it was found that the effect of suppressing the concentration of electric field on the low voltage pads **13** is not necessarily improved by increasing the number of second dummy conductor patterns **121**.

(255) The results of FIG. **19** are summarized as follows. It is preferable to provide the second withstand voltage enhancement structure **104**. The concentration of electric field on the low voltage pad ends (second withstand voltage holding region end) can thereby be relaxed in the region between the low voltage pads **13** and the upper coils **21A** and **21B**. Also, the concentration of electric field on the low voltage pad ends (second withstand voltage holding region end) can be relaxed in a region between the low voltage pads **13** and the second pads **34**.

(256) Preferably, the protrusion amount **Z2** of the second withstand voltage enhancement structure **104** exceeds 0 μm . That “the protrusion amount **Z2** exceeds 0 μm ” practically means that a second dummy conductor pattern **121** is formed.

(257) The number of the second dummy conductor patterns **121** may be not more than 12. In this case, the protrusion amount Z2 of the second withstand voltage enhancement structure **104** may exceed 0 μm and be not more than 50 μm . In this case, the electric field strength on the second withstand voltage enhancement structure **104** becomes not more than 35 kV/ μm and the concentration of electric field on the low voltage pad ends (second withstand voltage holding region end) can be relaxed. In this case, an absolute value of a difference between the electric field strength at the second withstand voltage enhancement structure end and the electric field strength at the upper coil ends may be not more than 10 kV/ μm .

(258) The number of the second dummy conductor patterns **121** may be not more than 6. In this case, the protrusion amount Z2 of the second withstand voltage enhancement structure **104** may exceed 0 μm and be not more than 25 μm . In this case, the electric field strength on the low voltage pad ends becomes not more than 35 kV/mm and the concentration of electric field on the low voltage pad ends (second withstand voltage holding region end) can be relaxed. In this case, the absolute value of the difference between the electric field strength at the second withstand voltage enhancement structure end and the electric field strength at the upper coil ends may be not more than 5 kV/mm.

(259) The number of the second dummy conductor patterns **121** may be not more than 3. In this case, the protrusion amount Z2 of the second withstand voltage enhancement structure **104** may exceed 0 μm and be not more than 10 μm . In this case, the electric field strength on the low voltage pad ends becomes not more than 30 kV/mm and the concentration of electric field on the low voltage pad ends (second withstand voltage holding region end) can be relaxed. In this case, the absolute value of the difference between the electric field strength at the second withstand voltage enhancement structure end and the electric field strength at the upper coil ends may be not more than 5 kV/mm.

(260) To examine a relationship between the first pad side withstand voltage enhancement structure **118** and the electric field strength, three samples A3, B3, and C3 were prepared as indicated in Table 3 below. With the three samples A3, B3, and C3, the second pitches PTa to PTf (see also FIG. **14**) are respectively set to the values as indicated in Table 3 below.

(261) In the following, end portions of the second pads **34** at the low voltage pads **13** (low voltage layer wirings **53**) side shall be referred to simply as the “second pad ends.” Also, an end portion of the first pad side withstand voltage enhancement structure **118** (first withstand voltage enhancement structure **103**) at the low voltage pads **13** (low voltage layer wirings **53**) side shall be referred to simply as the “first pad side withstand voltage enhancement structure end.”

(262) TABLE-US-00003

TABLE 3	Reference	Example	Sample A3	Sample B3	Sample C3	Second pitch PTa
20 μm	1 μm	5 μm	Second pitch PTb	20 μm	10 μm	10 μm
Second pitch PTc	20 μm	20 μm	30 μm	Second pitch PTd	20 μm	20 μm
30 μm	Second pitch PTe	10 μm	20 μm	10 μm	Second pitch PTf	1 μm
20 μm	5 μm	Total value	91 μm	91 μm	90 μm	Electric field
66 kV/mm	25 kV/mm	9 kV/mm	5 kV/mm	strength		

(263) Here, the electric field strength at the first pad side withstand voltage enhancement structure end (second pad ends) was determined for samples A3 to C3. The electric field strength at the second pad end of the electronic component according to the reference example is also shown in Table 3.

(264) The electric field strength at the first pad side withstand voltage enhancement structure end in sample A3 was kV/ μm . The electric field strength at the first pad side withstand voltage enhancement structure end in sample B3 was 9 kV/ μm . The electric field strength at the first pad side withstand voltage enhancement structure end in sample C3 was kV/mm.

(265) From the above, it was found that even when total values of the second pitches PTa to PTf are set to be substantially equal, the electric field strength at the second pad ends is changed by differing the values of the second pitches PTa to PTf.

(266) In particular, it was found that the electric field strength at the second pad ends can be

relaxed appropriately by setting the second pitch PTa to not more than 10 μm as in sample B3 and sample C3.

(267) The results of Table 3 are summarized as follows. It is preferable to form the first pad side withstand voltage enhancement structure **118** (first withstand voltage enhancement structure **103**) along the second pads **34**. The concentration of electric field on the second pad ends can thereby be relaxed.

(268) Preferably, the second pitch PTa between the first dummy conductor pattern **108** most proximal to the second pads **34** and the second pads **34** is not more than the second pitches PTb to PTf. The trailing ends of the electric fields that are formed between the upper coils **21A** and **21B** and the lower coils can thereby be shifted from the second pad ends to the first dummy conductor pattern **108** most proximal to the second pad ends. The concentration of electric field on the second pad ends can thereby be relaxed appropriately.

(269) Also, the second pitch PTa is preferably not more than a vertical direction distance L2 between the upper coils **21A** and **21B** and the lower coils **20** (PTa L2). The vertical direction distance L2 is the total thickness L2 of the insulating layers **28** between the lower coils **20** and the upper coils **21**.

(270) The second pitch PTa most proximal to the second pads **34** is preferably not more than 10 μm (PTa 10 μm). The electric field strength at the first pad side withstand voltage enhancement structure end thereby becomes not more than 10 kV/mm and the electric field strength at the second pad ends can be decreased effectively.

(271) The second pitches PTa to PTf of the first pad side withstand voltage enhancement structure **118** do not necessarily have to be set to the values in Table 3 above. The second pitches PTa to PTf of the first pad side withstand voltage enhancement structure **118** may be set to any of various values based on the electric field strength to be relaxed between the second pads **34** and the low voltage pads **13**.

(272) The second pitches PTa to PTf of the second pad side withstand voltage enhancement structure **119** do not necessarily have to be set to be the same as the second pitches PTa to PTf of the first pad side withstand voltage enhancement structure **118**. The second pitches PTa to PTf of the second pad side withstand voltage enhancement structure **119** may be set to any of various values based on the electric field strength to be relaxed between the second pads **34** and the shield layer **69**.

(273) FIG. **20** is a graph comparing an average dielectric breakdown voltage of the electronic component according to the reference example of the present invention and an average dielectric breakdown voltage of the electronic component **101**. In FIG. **20**, the ordinate represents the average dielectric breakdown voltage [kVrms].

(274) Referring to FIG. **20**, the average dielectric breakdown voltage of the electronic component **101** was increased by 6.2% with respect to the average dielectric breakdown voltage of the electronic component according to the reference example. From this, it was found that the average dielectric breakdown voltage can be improved by the withstand voltage enhancement structure **102**.

(275) As described above, with the electronic component **101**, the concentration of electric field on respective members can be relaxed by the withstand voltage enhancement structure **102**. The electronic component **101** that enables improvement of the dielectric breakdown resistance can thus be provided.

(276) FIG. **21** is a diagram of a portion corresponding to FIG. **16** and is a sectional view of an electronic component **131** according to a third preferred embodiment of the present invention. With this embodiment, structures corresponding to structures of the electronic component **101** are provided with the same reference symbols and description thereof is omitted.

(277) Referring to FIG. **21**, the electronic component **131** includes the resin films **77** (see also FIG. **3**, etc.). In this embodiment, each resin film **77** overlaps with each first withstand voltage enhancement structure **103** in plan view. More specifically, the resin film **77** covers an entirety of

the first withstand voltage enhancement structure **103**.

(278) The upper coils **21A** and **21B** and the first withstand voltage enhancement structure **103** are thus arranged within a region surrounded by an outer peripheral edge of the resin film **77** in plan view.

(279) The resin film **77** may cover a front surface of a portion of the insulating layer laminated structure **27**. The resin film **77** may cover an entirety of the front surface of the insulating layer laminated structure **27**.

(280) With the electronic component **131** described above, the same effects as the effects described with the first preferred embodiment can be exhibited in addition to the effects described with the second preferred embodiment.

(281) FIG. **22** is a diagram of a portion corresponding to FIG. **14** and is a diagram for describing the planar structure at the first upper coil **21A** side of an electronic component **141** according to a fourth preferred embodiment of the present invention. With this embodiment, structures corresponding to the structures of the electronic component **101** are provided with the same reference symbols and description thereof is omitted.

(282) In the electronic component **141**, the spiral pattern **105** of each of the upper coils **21A** and **21B** include a first spiral pattern **142** and a second spiral pattern **143**. The first spiral pattern **142** is routed to be wound outwardly in regions facing the lower coils **20** in plan view.

(283) The second spiral pattern **143** is routed to be wound outwardly continuously from the first spiral pattern **142** in regions outside the lower coils **20** in plan view. The second spiral pattern **143** is connected to the outer coil end wiring **96**.

(284) The first withstand voltage enhancement structure **103** can include the second spiral pattern **143**. That is, the first coil side withstand voltage enhancement structure **116** and the second coil side withstand voltage enhancement structure **117** can each include the second spiral pattern **143**.

(285) In this embodiment, a total protrusion amount **Z4** of the second spiral pattern **143** and the first withstand voltage enhancement structure **103** with respect to the outer contours of the lower coils **20** applies in place of the protrusion amount **Z1**. The total protrusion amount **Z4** may exceed 0 μm and be not more than 100 μm .

(286) The total protrusion amount **Z4** is defined by a sum ($=Z3+Z1$) of a protrusion amount **Z3** of the second spiral pattern **143** with respect to the outer contours of the lower coils **20** and the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** with respect to the outer contours of the second spiral pattern **143** (outer contours of the upper coils **21A** and **21B**).

(287) The total protrusion amount **Z4** may be adjusted by changing the number of turns and the winding pitch PTL of the second spiral pattern **143**. The total protrusion amount **Z4** may be adjusted by changing the number of the first dummy conductor patterns **108** and the value of the first pitch PT1 thereof.

(288) Next, a relationship between the second spiral pattern **143** and the electric field strength shall be described. Here, to examine the relationship between the second spiral pattern **143** and the electric field strength, three samples A4, B4, and C4, shown in FIG. **23**, FIG. **24**, and FIG. **25** were prepared.

(289) FIG. **23** is a plan view of an upper coil **21** (upper coil **21A** or **21B**) of sample A4 of the electronic component **141** shown in FIG. **22**. FIG. **24** is a plan view of an upper coil **21** (upper coil **21A** or **21B**) of sample B4 of the electronic component **141** shown in FIG. **22**. FIG. **25** is a plan view of an upper coil **21** (upper coil **21A** or **21B**) of sample C4 of the electronic component **141** shown in FIG. **22**.

(290) In each of FIG. **23**, FIG. **24**, and FIG. **25**, the upper coil **21** is represented by an elliptical annular shape and the outer contour of a lower coil **20** is represented by a broken line for convenience of description. The structure of the lower coils **20** is the same as the structure of the upper coils **21A** and **21B** with the exception of differing in the number of turns and therefore specific description shall be omitted in regard to FIG. **23**, FIG. **24**, and FIG. **25**.

(291) Also, with FIG. 23, FIG. 24, and FIG. 25, in order to examine the relationship between the second spiral pattern **143** and the electric field strength, the first withstand voltage enhancement structure **103** is not formed. That is, the protrusion amount **Z1** of the first withstand voltage enhancement structure **103** is zero (protrusion amount **Z1**=0).

(292) Referring to FIG. 23, with sample A4, the number of turns of the lower coil **20** is 13. On the other hand, in the upper coils **21A** and **21B**, the number of turns of the first spiral pattern **142** is 13 and the number of turns of the second spiral pattern **143** is 2. The total protrusion amount **Z4** is not less than 8 μm and not more than 13 μm (here, approximately μm).

(293) Referring to FIG. 24, with sample B4, the number of turns of the lower coil **20** is 10. On the other hand, in the upper coils **21A** and **21B**, the number of turns of the first spiral pattern **142** is 10 and the number of turns of the second spiral pattern **143** is 5. The total protrusion amount **Z4** is not less than 17 μm and not more than 23 μm (here, approximately μm).

(294) Referring to FIG. 25, with sample C4, the number of turns of the lower coil **20** is 7. On the other hand, in the upper coils **21A** and **21B**, the number of turns of the first spiral pattern **142** is 7 and the number of turns of the second spiral pattern **143** is 8. The total protrusion amount **Z4** is not less than 27 μm and not more than 33 μm (here, approximately 30 μm).

(295) FIG. 26 is a graph of electric field strength measurement results of sample A4, sample B4, and sample C4. In FIG. 26, the ordinate represents the electric field strength [kV/mm] and the abscissa represents the total protrusion amount **Z4** [μm].

(296) In FIG. 26, a first plotted point **P11**, a second plotted point **P12**, a third plotted point **P13**, and a fourth plotted point **P14** are indicated.

(297) The first plotted point **P11** represents the electric field strength at the upper coil ends of the electronic component according to the reference example. The second plotted point **P12** represents the electric field strength at end portions of the second spiral pattern **143** of sample A4.

(298) The third plotted point **P13** represents the electric field strength at the end portions of the second spiral pattern **143** of sample B4. The fourth plotted point **P14** represents the electric field strength at the end portions of the second spiral pattern **143** of sample C4.

(299) Referring to the first plotted point **P11**, the electric field strength at the upper coil ends in the electronic component according to the reference example was 66 kV/mm.

(300) Referring to the second plotted point **P12**, the electric field strength at the end portions of the second spiral pattern **143** of sample A4 was not less than 30 kV/mm and not more than 35 kV/mm.

(301) Referring to the third plotted point **P13**, the electric field strength at the end portions of the second spiral pattern **143** of sample B4 was not less than 25 kV/mm and not more than 30 kV/mm.

(302) Referring to the fourth plotted point **P14**, the electric field strength at the end portions of the second spiral pattern **143** of sample C4 was not less than 25 kV/mm and not more than 30 kV/mm.

(303) The electric field strength at the upper coil ends of the electronic component according to the reference example was thus higher than the respective electric field strengths of the three samples A4, B4, and C4. That is, with the electronic component according to the reference example that does not have the second spiral pattern **143**, the concentration of electric field on the upper coil ends was significant. On the other hand, it was found that with samples A4, B4, and C4 each having the second spiral pattern **143**, the concentration of electric field is relaxed by the second spiral pattern **143**.

(304) From the above, it was found that the concentration of electric field on the upper coil ends is relaxed as long as the total protrusion amount **Z4** is not set to zero.

(305) FIG. 27 is a graph comparing the average dielectric breakdown voltage of the electronic component according to the reference example of the present invention, an average dielectric breakdown voltage of sample A4 shown in FIG. 23, an average dielectric breakdown voltage of sample B4 shown in FIG. 24, and an average dielectric breakdown voltage of sample C4 shown in FIG. 25. In FIG. 27, the ordinate represents the average dielectric breakdown voltage [kVrms].

(306) Referring to FIG. 27, the average dielectric breakdown voltage of sample A4 was increased

by 6.5% with respect to the average dielectric breakdown voltage of the electronic component according to the reference example. The average dielectric breakdown voltage of sample B4 was increased by 9.7% with respect to the average dielectric breakdown voltage of the electronic component according to the reference example.

(307) The average dielectric breakdown voltage of sample C4 was increased by 10.0% with respect to the average dielectric breakdown voltage of the electronic component according to the reference example.

(308) From this, it was found that the average dielectric breakdown voltage can be increased, that is, the dielectric breakdown resistance can be improved by increasing the total protrusion amount **Z4**.

(309) The results of FIG. **26** and FIG. **27** are summarized as follows. Each of the first coil side withstand voltage enhancement structure **116** and the second coil side withstand voltage enhancement structure **117** can include the second spiral patterns **143** of the upper coils **21A** and **21B**. Since the electric field strength is inversely proportional to distance, it is preferable to provide the first withstand voltage enhancement structure **103** and/or the second spiral pattern **143** in accordance with the electric field strength to be relaxed.

(310) The concentration of electric field on the second spiral pattern **143** can thus be relaxed in a region between the second spiral pattern **143** and the low voltage pads **13**. Also, the concentration of electric field on the second spiral pattern **143** can be relaxed in a region between the second spiral pattern **143** and the shield layer **69**.

(311) The total protrusion amount **Z4** may be not less than 5 μm and not more than 11 μm . In this case, the electric field strength at the end portions of the second spiral pattern **143** becomes not less than 30 kV/ μm and not more than 35 kV/ μm .

(312) The total protrusion amount **Z4** is preferably not less than 17 μm and not more than 23 μm . In this case, the electric field strength at the end portions of the second spiral pattern **143** becomes not less than 25 kV/ μm and not more than kV/mm.

(313) The total protrusion amount **Z4** is preferably not less than 27 μm and not more than 33 μm . In this case, the electric field strength at the end portions of the second spiral pattern **143** becomes not less than 25 kV/ μm and not more than kV/mm.

(314) As described above, with the electronic component **141**, substantially the same effects as the effects described with the second preferred embodiment can be exhibited.

(315) In this embodiment, in adjusting the total protrusion amount **Z4**, the number of turns of the upper coils **21** was made greater than the number of turns of the lower coils under a condition that a wire width and a pitch width of the lower coils **20** and a wire width and a pitch width of the upper coils **21** are respectively equal to each other.

(316) However, in adjusting the total protrusion amount **Z4**, at least one of the wire width, the pitch width, and the number of turns of the upper coils **21** may be changed. Also, in adjusting the total protrusion amount **Z4**, at least one of the wire width, the pitch width, and the number of turns of the lower coils **20** may be changed.

(317) Further, the respective conditions of the lower coils **20** and the respective conditions of the upper coils **21** may be changed respectively. In one configuration example, the wire width of the upper coils **21** may be set to a value greater than the wire width of the lower coils **20** while the number of turns of the lower coils **20** and the number of turns of the upper coils **21** are set to the same value.

(318) In another configuration example, the pitch width of the upper coils **21** may be set to a value greater than the pitch width of the lower coils **20** while the wire width and the number of turns of the lower coils **20** and the wire width and the number of turns of the upper coils **21** are respectively set to the same values.

(319) Obviously, in increasing the total protrusion amount **Z4**, at least two among the number of turns, the wire width, and the pitch width of the upper coils **21** may be set to larger values than

those of the lower coils **20**.

(320) FIG. **28** is a sectional view for describing an electronic component **151** according to a fifth preferred embodiment of the present invention. With this embodiment, structures corresponding to the structures of the electronic component **101** are provided with the same reference symbols and description thereof is omitted.

(321) The electronic component **151** has a second insulating layer **152** that covers a region above the insulating layer laminated structure **27** as a first insulating layer. The second insulating layer **152** covers the protective film **75**, the passivation film **76**, the resin films **77**, etc., altogether.

(322) As mentioned above, the insulating layer laminated structure **27** includes the etching stopper films **29** and the interlayer insulating films **30**. The etching stopper films **29** include, for example, an SiN film, an SiC film, an SiCN film, etc. The interlayer insulating films **30** include, for example, an SiO.sub.2 film.

(323) The insulating layer laminated structure **27** thus has a first dielectric breakdown strength **S1** of not less than 5.0 MV/cm. The first dielectric breakdown strength **S1** of the insulating layer laminated structure **27** is preferably not less than 8.0 MV/cm and not more than 15 MV/cm.

(324) The insulating layer laminated structure **27** may include an insulating film constituted of an insulating material other than SiN, SiC, SiCN, and SiO.sub.2 as long as the first dielectric breakdown strength **S1** is not less than 5.0 MV/cm. An insulator (SiO.sub.2 or SiN, etc.) having the first dielectric breakdown strength **S1** of not less than 8.0 MV/cm and not more than 10 MV/cm may be selected as the insulating layer laminated structure **27**.

(325) The second insulating layer **152** has a second dielectric breakdown strength **S2** not more than the first dielectric breakdown strength **S1** ($S2 \leq S1$). More specifically, the second dielectric breakdown strength **S2** is less than the first dielectric breakdown strength **S1** ($S2 < S1$).

(326) The second dielectric breakdown strength **S2** of the second insulating layer **152** may be not less than 0.1 MV/cm and not more than 0.5 MV/cm. A resin (epoxy resin or polyimide resin, etc.) having the second dielectric breakdown strength **S2** of not less than 0.1 MV/cm and not more than 0.3 MV/cm may be selected as the second insulating layer **152**.

(327) In this embodiment, the second insulating layer **152** is constituted of a resin layer. The resin layer may include at least one resin among an epoxy resin, a polyimide resin, and a polybenzoxazole resin. The resin layer may be formed of a molded resin including at least one resin among an epoxy resin, a polyimide resin, and a polybenzoxazole resin.

(328) If the second insulating layer **152** includes a molded resin, the second insulating layer **152** may be formed by a portion of the resin package **2** (see FIG. **1**) of the electronic component module **1**. That is, the electronic component **151** in a state of being arranged in an interior of the resin package **2** may include a portion of the resin package **2** that covers the region above the insulating layer laminated structure **27**.

(329) Although there is present a difference due to having or not having the resin films **77**, such a configuration is practically the same as a configuration where the electronic component **101** according to the second preferred embodiment or the electronic component **131** according to the third preferred embodiment or the electronic component **141** according to the fourth preferred embodiment is arranged in the interior of the resin package **2**.

(330) The upper coils **21A** and **21B** form, with the low voltage layer wirings **53**, an electric field having a first value **R1** not more than the first dielectric breakdown strength **S1** ($R1 \leq S1$). More specifically, the first value **R1** is less than the first dielectric breakdown strength **S1** ($R1 < S1$).

(331) The first withstand voltage enhancement structure **103** forms, with the low voltage layer wirings **53**, an electric field having a second value **R2** not less than the first value **R1** and not more than the first dielectric breakdown strength **S1** ($R1 \leq R2 \leq S1$). More specifically, the second value **R2** exceeds the first value **R1** and is less than the first dielectric breakdown strength **S1** ($R1 < R2 < S1$).

(332) The first withstand voltage enhancement structure **103** increases the electric field between the

upper coils **21A** and **21B** and the low voltage layer wirings **53** by shortening of distance while relaxing the concentration of electric field on the upper coils **21A** and **21B**.

(333) The second withstand voltage enhancement structure **104** forms, with the first withstand voltage enhancement structure **103**, an electric field having a third value $R3$ not less than the second value $R2$ and not more than the first dielectric breakdown strength $S1$ ($R2 \leq R3 \leq S1$). More specifically, the third value $R3$ exceeds the second value $R2$ and is less than the first dielectric breakdown strength $S1$ ($R2 < R3 < S1$).

(334) The second withstand voltage enhancement structure **104** increases the electric field between the upper coils **21A** and **21B** and the low voltage layer wirings **53** by shortening of distance while relaxing the concentration of electric field on the low voltage layer wirings **53**.

(335) The high voltage pads **14** form, with the low voltage pads **13**, an electric field having a fourth value $R4$ not more than the second dielectric breakdown strength $S2$ ($R4 \leq S2$). More specifically, the fourth value $R4$ is less than the second dielectric breakdown strength $S2$ ($R4 < S2$).

(336) The electric field between the upper coils **21A** and **21B** and the low voltage layer wirings **53** is practically determined by a distance between the first withstand voltage enhancement structure **103** and the second withstand voltage enhancement structure **104**. Similarly, the electric field between the upper coils **21A** and **21B** and the shield layer **69** is practically determined by a distance between the first withstand voltage enhancement structure **103** and the shield layer **69**.

(337) The first withstand voltage enhancement structure **103** thereby functions as a first electric field enhancement structure that increases the electric field between the upper coils **21A** and **21B** and the low voltage layer wirings **53** and the electric field between the upper coils **21A** and **21B** and the shield layer **69**. Also, the second withstand voltage enhancement structure **104** functions as a second electric field enhancement structure that increases the electric field between the upper coils **21A** and **21B** and the low voltage layer wirings **53**.

(338) More specifically, the first proximal region **112** of the first withstand voltage enhancement structure **103** forms a first coil side electric field enhancement structure that increases the electric field between the first upper coil **21A** and the low voltage layer wirings **53**. Also, the first proximal region **112** of the first withstand voltage enhancement structure **103** forms the first coil side electric field enhancement structure that increases the electric field between the first upper coil **21A** and the shield layer **69**.

(339) The second proximal region **113** of the first withstand voltage enhancement structure **103** forms a second coil side electric field enhancement structure that increases the electric field between the second upper coil **21B** and the low voltage layer wirings **53**. Also, the second proximal region **113** of the first withstand voltage enhancement structure **103** forms the second coil side electric field enhancement structure that increases the electric field between the second upper coil **21B** and the shield layer **69**.

(340) The first connection region **114** of the first withstand voltage enhancement structure **103** forms a first pad side electric field enhancement structure that increases the electric field between the second pads **34** and the low voltage layer wirings **53**. Also, the first connection region **114** of the first withstand voltage enhancement structure **103** forms the first pad side electric field enhancement structure that increases the electric field between the second pads **34** and the shield layer **69**.

(341) The connection region **115** of the first withstand voltage enhancement structure **103** forms the second pad side electric field enhancement structure that increases the electric field between the second pads **34** and the shield layer **69**.

(342) FIG. **29** is a diagram for describing an effect of the electronic component **151** shown in FIG. **28**. FIG. **30** is a diagram for describing the effect of the electronic component **151** shown in FIG. **28**. For convenience of description, a lower coil **20**, an upper coil **21**, the withstand voltage enhancement structure **102**, and other structures are simplified in FIG. **29** and FIG. **30**.

(343) With the electronic component **151** according to the present preferred embodiment, the upper

coils **21A** and **21B** and the lower coils **20** are formed inside the insulating layer laminated structure **27** having the first dielectric breakdown strength **S1**.

(344) Referring to FIG. **29**, as described with the second preferred embodiment, if the withstand voltage enhancement structure **102** is not formed, an electric field concentrates at the upper coil end. Especially, if a plan view area of the upper coils **21A** and **21B** is not more than a plan view area of the lower coils **20**, the electric field wraps around over a boundary region between the insulating layer laminated structure **27** and the second insulating layer **152** to an upper side of the upper coil end and the electric field thus tends to concentrate at the upper coil end.

(345) If the electric field strength at the upper coil end exceeds the second dielectric breakdown strength **S2** of the second insulating layer **152**, there is a possibility of dielectric breakdown occurring at the second insulating layer **152**.

(346) On the other hand, referring to FIG. **30**, if the first withstand voltage enhancement structure **103** (withstand voltage enhancement structure **102**) is formed, the concentration of electric field on the upper coil end, etc., is relaxed as described with the second preferred embodiment.

(347) The first withstand voltage enhancement structure **103** protrudes outward from the outer contours of the upper coils **21A** and **21B** and can therefore shield the electric field formed between the lower coils **20** and the upper coils **21A** and **21B**. The electric field is thereby suppressed from extending over the boundary region between the insulating layer laminated structure **27** and the second insulating layer **152**.

(348) Moreover, the second withstand voltage enhancement structure **104** (withstand voltage enhancement structure **102**) protrudes from the outer contours of the low voltage pads **13** toward the upper coils **21A** and **21B** side. The electric field between the upper coils **21A** and **21B** and the low voltage layer wirings **53** is thereby practically determined by the distance between the first withstand voltage enhancement structure **103** and the second withstand voltage enhancement structure **104**.

(349) Therefore, while the electric field strength increases in the insulating layer laminated structure **27** having the first dielectric breakdown strength **S1** not less than the second dielectric breakdown strength **S2** ($S1 \geq S2$), the electric field strength decreases in the second insulating layer **152** having the second dielectric breakdown strength **S2** not more than the first dielectric breakdown strength **S1** ($S2 \leq S1$).

(350) With the electronic component **151**, the electric field strength at the second insulating layer **152** side that is low in dielectric breakdown strength is decreased by intentionally increasing the electric field strength at the insulating layer laminated structure **27** side that is high in dielectric breakdown strength. The dielectric breakdown of the second insulating layer **152** due to the concentration of electric field can thus be suppressed. Consequently, the electronic component **151** that enables improvement of the withstand voltage can thus be provided.

(351) FIG. **31** is a diagram for describing the planar structure of an electronic component **161** according to a sixth preferred embodiment of the present invention. FIG. **32** is a diagram for describing the planar structures of low voltage side capacitor conductor films **162** of the electronic component **161** shown in FIG. **31**.

(352) FIG. **33** is a diagram for describing the planar structures of high voltage side capacitor conductor films **163** of the electronic component **161** shown in FIG. **31**. FIG. **34** is a sectional view taken along line XXXIV-XXXIV shown in FIG. **31**. In the following, structures corresponding to the structures of the electronic component **101** are provided with the same reference symbols and description thereof is omitted.

(353) Referring to FIG. **31** to FIG. **34**, with the electronic component **161**, the lower coils **20** and the upper coils **21**, the inner coil end wirings **37** and the outer coil end wiring **96**, and the inner coil end wirings **49** and the outer coil end wiring **97** are not formed.

(354) With the electronic component **161**, the low voltage side capacitor conductor films **162** are formed in place of the lower coils **20**, the inner coil end wirings **49**, and the outer coil end wiring

97. Also, the high voltage side capacitor conductor films **163** are formed in place of the upper coils **21**, the inner coil end wirings **37**, and the outer coil end wiring **96**.

(355) The low voltage side capacitor conductor films **162** are formed as examples of low voltage conductor patterns. The high voltage side capacitor conductor films **163** are formed as examples of high voltage conductor patterns. The low voltage side capacitor conductor films **162** and the high voltage side capacitor conductor films **163** are formed by simply changing mask patterns for forming the lower coils **20** and the upper coils **21**.

(356) With this embodiment, two low voltage side capacitor conductor films **162** are formed at an interval along the first direction A. Also, two high voltage side capacitor conductor films **163** are formed at an interval along the first direction A.

(357) The respective high voltage side capacitor conductor films **163** face the low voltage side capacitor conductor films **162**, respectively, across at least one insulating layer **28**. A vertical direction distance L2 between the high voltage side capacitor conductor films **163** and the low voltage side capacitor conductor films **162** may be not less than 12.0 μm and not more than 16.8 μm . The vertical direction distance L2 is the total thickness L2 of the insulating layers **28** between the high voltage side capacitor conductor films **163** and the low voltage side capacitor conductor films **162**.

(358) A first capacitance **164** is formed by a low voltage side capacitor conductor film **162** and a high voltage side capacitor conductor film **163** that face each other at one side in the first direction A. A second capacitance **165** is formed by the low voltage side capacitor conductor film **162** and the high voltage side capacitor conductor film **163** that face each other at the other side in the first direction A.

(359) The structure at the first capacitance **164** side and the structure at the second capacitance **165** side are substantially the same. In the following, the structure at the first capacitance **164** side shall be described as an example, and for the structure at the second capacitance **165** side, the same reference symbols as the first capacitance **164** side are provided and description thereof is omitted.

(360) In the first capacitance **164**, the low voltage side capacitor conductor film **162** and the high voltage side capacitor conductor film **163** are respectively formed to flat plate shapes. In this embodiment, the low voltage side capacitor conductor film **162** and the high voltage side capacitor conductor film **163** are formed to elliptical shapes in plan view.

(361) The planar shapes of the low voltage side capacitor conductor film **162** and the high voltage side capacitor conductor film **163** are arbitrary and not restricted to elliptical shapes. The low voltage side capacitor conductor film **162** and the high voltage side capacitor conductor film **163** may thus be formed respectively to circular shapes or polygonal shapes (for example, quadrilateral shapes).

(362) The low voltage side capacitor conductor film **162** is electrically connected to the low voltage pads **13** via the penetrating wirings **51** and the lead-out wirings **52**. The high voltage side capacitor conductor film **163** is electrically connected to the high voltage pads **14** via the vias **38**.

(363) In this embodiment, the low voltage pads **13** are formed in a region outside the high voltage side capacitor conductor film **163** in plan view. In this embodiment, the high voltage pads **14** are formed in a region facing the high voltage side capacitor conductor film **163** in plan view.

(364) As with the electronic component **101**, the electronic component **161** includes the withstand voltage enhancement structures **102** of conductive property. Each withstand voltage enhancement structure **102** is formed in a region between members of the low voltage side and members of the high voltage side. The members of the low voltage side include, for example, the low voltage pads **13**, the shield layer **69**, etc., that are fixed at the reference potential or the ground potential.

(365) The members of the high voltage side include, for example, the high voltage pads **14**, the high voltage side capacitor conductor film **163**, etc. The withstand voltage enhancement structure **102** suppresses withstand voltage degradation due to an electric field that is formed in the region between the members of the low voltage side and the members of the high voltage side. The

withstand voltage enhancement structure **102** includes the first withstand voltage enhancement structure **103** at the high voltage side and the second withstand voltage enhancement structure **104** at the low voltage side.

(366) In this embodiment, the first withstand voltage enhancement structure **103** is, in plan view, formed along an outer contour of the low voltage side capacitor conductor film **162** such as to protrude further outward than the outer contour of the low voltage side capacitor conductor film **162**. The first withstand voltage enhancement structure **103** surrounds the high voltage side capacitor conductor film **163** such as to demarcate the high voltage side capacitor conductor film **163** from other regions.

(367) The first withstand voltage enhancement structure **103** is formed to be equipotential to the high voltage side capacitor conductor film **163**. In this embodiment, the first withstand voltage enhancement structure **103** includes a single first dummy conductor pattern **108** of ring shape (elliptical ring shape) in plan view.

(368) The first dummy conductor pattern **108** forms a shield layer. In this embodiment, the first dummy conductor pattern **108** is formed integral to an outer peripheral edge of the high voltage side capacitor conductor film **163**.

(369) With the exception of the point that the first dummy conductor pattern **108** is constituted of a single pattern, the arrangement of the first withstand voltage enhancement structure **103** (first dummy conductor pattern **108**) is the same as the first withstand voltage enhancement structure **103** (first dummy conductor patterns **108**) according to the electronic component **101**. Specific description of the first withstand voltage enhancement structure **103** (first dummy conductor pattern **108**) is omitted.

(370) The second withstand voltage enhancement structure **104** is formed in a region between the high voltage side capacitor conductor film **163** and the low voltage layer wirings **53** (low voltage pads **13**) in plan view. The second withstand voltage enhancement structure **104** extends in a line shape along the first direction A.

(371) The second withstand voltage enhancement structure **104** is formed along the plurality of low voltage layer wirings **53** (low voltage pads **13**) in plan view. The second withstand voltage enhancement structure **104** extends in the line shape along the first direction A such as to pass along the plurality of low voltage pads **13**. The second withstand voltage enhancement structure **104** thereby demarcates the plurality of low voltage pads **13** (low voltage layer wirings **53**) respectively from the upper coils **21A** and **21B**.

(372) In this embodiment, the second withstand voltage enhancement structure **104** includes a single second dummy conductor pattern **121**. The second dummy conductor pattern **121** forms a shield layer. As in the electronic component **101**, the second withstand voltage enhancement structure **104** may include the second dummy conductor pattern group **122** formed by the assembly of a plurality of the second dummy conductor patterns **121**.

(373) The arrangement of the second withstand voltage enhancement structure **104** (second dummy conductor pattern **121**) is the same as the second withstand voltage enhancement structure **104** (second dummy conductor patterns **121**) according to the electronic component **101**. Specific description of the second withstand voltage enhancement structure **104** (second dummy conductor pattern **121**) is omitted.

(374) Even when the low voltage side capacitor conductor films **162** and the high voltage side capacitor conductor films **163** are included as in the electronic component **161** described above, the same effects as the effects described for the electronic component **101** can be exhibited.

(375) As with the electronic component **101**, the electronic component **161** may include the second insulating layer **152** that covers the region above the insulating layer laminated structure **27** (see also FIG. **28**). In this case, the same effects as the effects described with FIG. **29** and FIG. can be exhibited.

(376) As with the electronic component **6** and the electronic component **131**, the electronic

component **161** may include the resin films **77** (see also FIG. 3, etc.). Each resin film **77** may overlap with the corresponding first withstand voltage enhancement structure **103** in plan view. The resin film **77** may cover the entirety of the first withstand voltage enhancement structure **103**.

(377) The high voltage side capacitor conductor film **163** and the first withstand voltage enhancement structure **103** may be arranged within the region surrounded by the outer peripheral edge of the resin film **77** in plan view. The resin film **77** may cover the front surface of a portion of the insulating layer laminated structure **27**. The resin film **77** may cover the entirety of the front surface of the insulating layer laminated structure **27**. In this case, the same effects as the effects described for the electronic component **6** and the electronic component **131** can be exhibited.

(378) FIG. 35 is a sectional view for describing an electronic component **171** according to a seventh preferred embodiment of the present invention. In the following, structures corresponding to structures of the electronic component **161** are provided with the same reference symbols and description thereof is omitted.

(379) With the electronic component **171**, the first withstand voltage enhancement structure **103** is formed at an interval from the high voltage side capacitor conductor film **163**. The first withstand voltage enhancement structure **103** is formed to be equipotential to the high voltage side capacitor conductor film **163**.

(380) The first withstand voltage enhancement structure **103** may be connected to the high voltage side capacitor conductor film **163** via a connection wiring (not shown). The connection wiring may be formed in the same layer as the first withstand voltage enhancement structure **103** and the high voltage side capacitor conductor film **163**. The connection wiring may be formed in a layer differing from that of the first withstand voltage enhancement structure **103** and the high voltage side capacitor conductor film **163**.

(381) The first withstand voltage enhancement structure **103** includes the first dummy conductor pattern **108** formed at an interval from the high voltage side capacitor conductor film **163**. As in the electronic component **101**, the first withstand voltage enhancement structure **103** may include the first dummy conductor pattern group **109** formed by the assembly of a plurality of the first dummy conductor patterns **108**.

(382) The arrangement of the first withstand voltage enhancement structure **103** (first dummy conductor pattern group **109**) is the same as the first withstand voltage enhancement structure **103** (first dummy conductor pattern group **109**) according to the electronic component **101**. Specific description of the first withstand voltage enhancement structure **103** (first dummy conductor pattern group **109**) is omitted.

(383) Even when the low voltage side capacitor conductor films **162** and the high voltage side capacitor conductor films **163** are included as in the electronic component **171** described above, the same effects as the effects described for the electronic component **101** can be exhibited.

(384) As with the electronic component **151**, the electronic component **171** may include the second insulating layer **152** that covers the region above the insulating layer laminated structure **27** (see also FIG. 28). In this case, the same effects as the effects described with FIG. 29 and FIG. can be exhibited.

(385) As with the electronic component **6** and the electronic component **131**, the electronic component **171** may include the resin films **77** (see also FIG. 3, etc.). The resin films **77** may overlap with the corresponding first withstand voltage enhancement structure **103** in plan view. The resin film **77** may cover the entirety of the first withstand voltage enhancement structure **103**.

(386) The high voltage side capacitor conductor film **163** and the first withstand voltage enhancement structure **103** may be arranged within the region surrounded by the outer peripheral edge of the resin film **77** in plan view. The resin film **77** may cover the front surface of a portion of the insulating layer laminated structure **27**. The resin film **77** may cover the entirety of the front surface of the insulating layer laminated structure **27**. In this case, the same effects as the effects described for the electronic component **6** and the electronic component **131** can be exhibited.

(387) Although the preferred embodiments of the present invention were described above, with the present invention, various design changes may be applied within the scope of the matters described in the claims.

(388) With the first present embodiment, the resin films **77** cover entire peripheries of both second pads **34** of the high voltage pads **14**. However, as shown in FIG. **36**, the resin films **77** may selectively cover just sides of the second pads **34** toward the first region **39** at which the low voltage pads **13** are arranged.

(389) In this case, the resin films **77** are preferably formed such as to cover the upper coils **21** entirely at peripheries of the first pads **33** in plan view.

(390) For example, if a filler is included in the resin package **2** that seals the electronic component **6**, unless the upper coils **21** are covered by the resin films **77**, the upper coils **21** may receive damage (filler attack) due to the filler during sealing. However, if the upper coils **21** are entirely covered by resin films **77**, the problem of filler attack, etc., can be suppressed. The present structure is also applicable to the second to seventh preferred embodiments.

(391) With the first preferred embodiment, the resin films **77** are formed to overlap with the peripheral edges of the second pads **34**. However, as shown in FIG. **37**, the resin films **77** do not have to overlap with the peripheral edges of the second pads **34**.

(392) In this case, the resin films **77** may have openings **60** having a larger diameter than the pad openings **79** to expose the second pad **34**. The present structure is also applicable to the second to seventh preferred embodiments.

(393) In the first to fifth preferred embodiments, a thickness of the lower coils **20** may be not less than a thickness of the upper coils **21**. The thickness of the lower coils **20** may be not more than the thickness of the upper coils **21**.

(394) In the first to fifth preferred embodiments, the lower coils **20** may include at least one substance among gold, silver, copper, aluminum, titanium, titanium nitride, and tungsten. The upper coils **21** may include at least one substance among gold, silver, copper, aluminum, titanium, titanium nitride, and tungsten. From a perspective of cost and mass productivity, the lower coils **20** and the upper coils **21** preferably include copper or aluminum.

(395) In the first to fifth preferred embodiments, a width of the spiral patterns of the lower coils **20** may be not more than the width of the spiral patterns **105** of the upper coils **21A** and **21B**. Obviously, the width of the spiral patterns of the lower coils **20** may be not less than the width of the spiral patterns **105** of the upper coils **21A** and **21B**.

(396) In the second to fifth preferred embodiments, the first withstand voltage enhancement structure **103** at the first transformer **301** side and the first withstand voltage enhancement structure **103** at the second transformer **302** side may be formed integrally.

(397) In this case, the upper coils **21A** and **21B** and the outer coil end wiring **96** at the first transformer **301** side and the upper coils **21A** and **21B** and the outer coil end wiring **96** at the second transformer **302** side may be surrounded by the first withstand voltage enhancement structure **103** altogether.

(398) In the second to fifth preferred embodiments, the second withstand voltage enhancement structure **104** at the first transformer **301** side and the second withstand voltage enhancement structure **104** at the second transformer **302** side may be formed integrally.

(399) In this case, the second withstand voltage enhancement structure **104** may be formed such as to extend continuously along the low voltage pads **13** (low voltage wirings **53**) at the first transformer **301** side and the low voltage pads **13** (low voltage wirings **53**) at the second transformer **302** side.

(400) In the second to fifth preferred embodiments, the first proximal regions **112**, the second proximal regions **113**, the first connection regions **114**, and the second connection regions **115** may be formed respectively as separate members. The first proximal regions **112**, the second proximal regions **113**, the first connection regions **114**, and the second connection regions **115** may

respectively include first dummy conductor pattern groups **109** that are mutually independent.

(401) In the second to fifth preferred embodiments, the withstand voltage enhancement structures **102** may be formed in a layer differing from that of the upper coils **21A** and **21B**.

(402) In the second to fifth preferred embodiments, the first withstand voltage enhancement structures **103** and the second withstand voltage enhancement structures **104** may be formed in respectively different layers.

(403) For example, the second withstand voltage enhancement structures **104** may be formed in a layer lower than the upper coils **21A** and **21B** while the first withstand voltage enhancement structures **103** are formed in a layer higher than the upper coils **21A** and **21B**.

(404) Oppositely, the second withstand voltage enhancement structures **104** may be formed in a layer higher than the upper coils **21A** and **21B** while the first withstand voltage enhancement structures **103** are formed in a layer lower than the upper coils **21A** and **21B**.

(405) In the second to fifth preferred embodiments, each first withstand voltage enhancement structure **103** may include a single wide shield layer in place of the plurality of first dummy conductor patterns **108**. The shield layer may have the protrusion amount **Z1**. Even with such a structure, the same effects as the effects described with the respective preferred embodiments can be exhibited.

(406) In the second to fifth preferred embodiments, the plurality of first dummy conductor patterns **108** may be formed in mutually different layers. For example, any three of the first dummy conductor patterns **108** may be formed in the same layer as the upper coils **21A** and **21B** and the other three first dummy conductor patterns **108** may be formed in a layer one below.

(407) Also, for example, any two of the first dummy conductor patterns **108** may be formed in the same layer as the upper coils **21A** and **21B**, two other first dummy conductor patterns **108** may be formed in a layer one below the upper coils **21A** and **21B**, and the yet other two first dummy conductor patterns **108** may be formed in a layer one above the upper coils **21A** and **21B**.

(408) In the second to fifth preferred embodiments, each second withstand voltage enhancement structure **104** may include a single wide shield layer in place of the plurality of second dummy conductor patterns **121**. The shield layer may have the protrusion amount **Z2**. Even with such a structure, the same effects as the effects described with the respective preferred embodiments can be exhibited.

(409) In the second to fifth preferred embodiments, the plurality of second dummy conductor patterns **121** may be formed in mutually different layers. For example, any one of the second dummy conductor patterns **121** may be formed in the same layer as the upper coils **21A** and **21B** and the other two second dummy conductor patterns **121** may be formed in a layer one below.

(410) Also, for example, any one of the second dummy conductor patterns **121** may be formed in the same layer as the upper coils **21A** and **21B**, another second dummy conductor pattern **121** may be formed in a layer one below the upper coils **21A** and **21B**, and the yet other dummy conductor pattern **121** may be formed in a layer one above the upper coils **21A** and **21B**.

(411) In the second to fifth preferred embodiments, each second dummy conductor pattern group **122** may include a second dummy conductor pattern **121** that extends along the second direction **B** to an opposite side from the upper coils **21A** and **21B**.

(412) In the sixth and seventh preferred embodiments, a thickness of the low voltage side capacitor conductor films **162** may be not less than a thickness of the high voltage side capacitor conductor films **163**. The thickness of the low voltage side capacitor conductor films **162** may be not more than the thickness of the high voltage side capacitor conductor films **163**.

(413) In the sixth and seventh preferred embodiments, the low voltage side capacitor conductor films **162** may include at least one substance among gold, silver, copper, aluminum, titanium, titanium nitride, and tungsten.

(414) The high voltage side capacitor conductor films **163** may include at least one substance among gold, silver, copper, aluminum, titanium, titanium nitride, and tungsten. From a perspective

of cost and mass productivity, the low voltage side capacitor conductor films **162** and the high voltage side capacitor conductor films **163** preferably include copper or aluminum.

(415) In the sixth and seventh preferred embodiments, the first withstand voltage enhancement structure **103** at the first capacitance **164** side and the first withstand voltage enhancement structure **103** at the second capacitance **165** side may be formed integrally.

(416) In this case, the high voltage side capacitor conductor film **163** at the first capacitance **164** side and the high voltage side capacitor conductor film **163** at the second capacitance **165** side may be surrounded by the first withstand voltage enhancement structure **103** altogether.

(417) In the sixth and seventh preferred embodiments, the second withstand voltage enhancement structure **104** at the first capacitance **164** side and the second withstand voltage enhancement structure **104** at the second capacitance **165** side may be formed integrally.

(418) In this case, the second withstand voltage enhancement structure **104** may be formed such as to extend continuously along the low voltage pads **13** (low voltage wirings **53**) at the first capacitance **164** side and the low voltage pads **13** (low voltage wirings **53**) at the second capacitance **165** side.

(419) In the sixth and seventh preferred embodiments, the withstand voltage enhancement structures **102** may be formed in a layer differing from that of the high voltage side capacitor conductor films **163**.

(420) In the sixth and seventh preferred embodiments, the first withstand voltage enhancement structures **103** and the second withstand voltage enhancement structures **104** may be formed in respectively different layers. For example, the second withstand voltage enhancement structures **104** may be formed in a layer lower than the high voltage side capacitor conductor films **163** while the first withstand voltage enhancement structures **103** are formed in a layer higher than the high voltage side capacitor conductor films **163**.

(421) Oppositely, the second withstand voltage enhancement structures **104** may be formed in a layer higher than the high voltage side capacitor conductor films **163** while the first withstand voltage enhancement structures **103** are formed in a layer lower than the high voltage side capacitor conductor films **163**.

(422) If in the seventh preferred embodiment, a plurality (for example, six) of the first dummy conductor patterns **108** are formed, the plurality of first dummy conductor patterns **108** may be formed in mutually different layers.

(423) For example, any three of the first dummy conductor patterns **108** may be formed in the same layer as the high voltage side capacitor conductor films **163** and the other three first dummy conductor patterns **108** may be formed in a layer one below.

(424) Also, for example, any two of the first dummy conductor patterns **108** may be formed in the same layer as the high voltage side capacitor conductor films **163**, two other first dummy conductor patterns **108** may be formed in a layer one below the high voltage side capacitor conductor films **163**, and the yet other two first dummy conductor patterns **108** may be formed in a layer one above the high voltage side capacitor conductor films **163**.

(425) If in the sixth and seventh preferred embodiments, a plurality (for example, three) of the second dummy conductor patterns **121** are formed, the plurality of second dummy conductor patterns **121** may be formed in mutually different layers.

(426) For example, any one of the second dummy conductor patterns **121** may be formed in the same layer as the high voltage side capacitor conductor films **163** and the other two second dummy conductor patterns **121** may be formed in a layer one below.

(427) Also, for example, any one of the second dummy conductor patterns **121** may be formed in the same layer as the high voltage side capacitor conductor films **163**, another second dummy conductor pattern **121** may be formed in a layer one below the high voltage side capacitor conductor films **163**, and the yet other dummy conductor pattern **121** may be formed in a layer one above the high voltage side capacitor conductor films **163**.

(428) In the sixth and seventh preferred embodiments, each second dummy conductor pattern group **122** may include a second dummy conductor pattern **121** that extends along the second direction B to an opposite side from the high voltage side capacitor conductor films **163**.

(429) In the second to seventh preferred embodiments, the second dummy conductor pattern group **122** may be formed such as to surround one or a plurality of the low voltage pads **13** in plan view. In this case, the second dummy conductor patterns **121** included in the second dummy conductor pattern group **122** may be formed to shapes with ends having the open portions **110** as the first dummy conductor patterns **108** are.

(430) FIG. **38** is a plan view of an electronic component module **201** according to a modification example. With the present modification example, structures corresponding to structures of the electronic component module **1** are provided with the same reference symbols and description thereof is omitted.

(431) With the electronic component module **1** according to the first preferred embodiment, the controller chip **5**, the electronic component **6**, and the driver chip **7** are respectively formed as separate chips.

(432) On the other hand, with the electronic component module **201** according to the present modification example, portions of functions of an electronic component **101** are incorporated in the controller chip **5** and the driver chip **7**, respectively.

(433) More specifically, a first transformer **301** of the electronic component **101** are incorporated in the controller chip **5** and a second transformer **302** of the electronic component **101** are incorporated in the driver chip **7**. The controller chip and the driver chip **7** are thereby also formed respectively as electronic components.

(434) Three high voltage pads **14** pertaining to the first transformer **301** of the controller chip **5** are respectively connected via high voltage wires **303** to three high voltage pads **304** provided at the driver chip **7**. The first transformer **301** of the controller chip **5** is also electrically connected to an arbitrary low voltage lead **3** (an arbitrary low voltage pad **10**) used as a ground terminal.

(435) Three high voltage pads **14** pertaining to the second transformer **302** of the driver chip **7** are respectively connected via high voltage wires **305** to three high voltage pads **306** provided at the controller chip **5**. The second transformer **302** of the driver chip **7** is also electrically connected to an arbitrary low voltage lead **3** (an arbitrary low voltage pad **17**) used as the ground terminal.

(436) When the first transformer **301** of the electronic component **101** is incorporated in the controller chip **5**, the first transformer **301** is built in using a wiring material of the controller chip **5**. Therefore, the lower coils **20**, the upper coils **21**, wiring members connecting the lower coils **20** and the upper coils **21**, etc., included in the first transformer **301** become the same in material as the wiring material of the controller chip **5**.

(437) For example, if the wiring material of the controller chip **5** is copper, the lower coils **20**, the upper coils **21**, the wiring members connecting the lower coils **20** and the upper coils **21**, etc., are formed of copper. If the wiring material of the electronic component **101** includes copper and aluminum, the lower coils **20**, the upper coils **21**, the wiring members connecting the lower coils **20** and the upper coils **21**, etc., are formed of copper and/or aluminum.

(438) The upper coils **21** may be formed of copper while the lower coils **20** are formed of aluminum. The upper coils **21** may be formed of aluminum while the lower coils **20** are formed of copper.

(439) When the second transformer **302** of the electronic component **101** is incorporated in the driver chip **7**, the second transformer **302** is built in using a wiring material of the driver chip **7**. Therefore, the lower coils **20**, the upper coils **21**, wiring members connecting the lower coils **20** and the upper coils **21**, etc., included in the second transformer **302** become the same in material as the wiring material of the driver chip **7**.

(440) For example, if the wiring material of the driver chip **7** is copper, the lower coils **20**, the upper coils **21**, the wiring members connecting the lower coils **20** and the upper coils **21**, etc., are

formed of copper. If the wiring material of the electronic component **101** includes copper and aluminum, the lower coils **20**, the upper coils **21**, the wiring members connecting the lower coils **20** and the upper coils **21**, etc., are formed of copper and/or aluminum.

(441) The upper coils **21** may be formed of copper while the lower coils **20** are formed of aluminum. The upper coils **21** may be formed of aluminum while the lower coils **20** are formed of copper.

(442) With the present modification example, an example where the first transformer **301** according to the first preferred embodiment is incorporated in the controller chip **5**. However, the first transformer **301** that includes the withstand voltage enhancement structure **102** according to the second to fourth preferred embodiments may be incorporated in the controller chip **5** instead.

(443) If the first transformer **301** that includes the withstand voltage enhancement structure **102** according to the third preferred embodiment is incorporated in the controller chip **5**, substantially an entirety of a device formation surface in which the controller IC is built may be covered by the resin film **77** in the controller chip **5**.

(444) With the present modification example, an example where the second transformer **302** according to the first preferred embodiment is incorporated in the driver chip **7**. However, the first transformer **301** that includes the withstand voltage enhancement structure **102** according to the second to fourth preferred embodiments may be incorporated in the driver chip **7** instead.

(445) If the second transformer **302** that includes the withstand voltage enhancement structure **102** according to the third preferred embodiment is incorporated in the driver chip **7**, substantially an entirety of a device formation surface in which the driver IC is built may be covered by the resin film **77** in the driver chip **7**.

(446) Examples of features extracted from the present description and drawings are indicated below. [Item 1] An electronic component including an insulating layer, a low voltage coil formed inside the insulating layer, a high voltage coil formed inside the insulating layer such as to face the low voltage coil in an up/down direction, high voltage pads including a first pad that is arranged such as to face a formation region of the high voltage coil in a thickness direction of the insulating layer and a second pad that is arranged such as to avoid the formation region of the high voltage coil in the thickness direction and being electrically connected, on the insulating layer, to the high voltage coil, a low voltage pad being connected, on the insulating layer, to the low voltage coil, and a resin film selectively formed on the insulating layer such as to cover a periphery of the first pad and a periphery of the second pad.

(447) According to this arrangement, a withstand voltage between the high voltage pads and the low voltage pad can be improved because the peripheries of both the first pad and the second pad of the high voltage pads are covered by the resin film. [Item 2] The electronic component according to Item 1, where, on the insulating layer, a first space and a second space are formed with the high voltage pads in between, the low voltage pad is selectively formed in the first space, and the resin film covers at least a periphery of the second pad at the first space side and the first pad. [Item 3] The electronic component according to Item 2, where the resin film covers a periphery of the second pad at the second space side and the first pad. [Item 4] The electronic component according to Item 3, where the resin film covers the periphery of the first pad and the periphery of the second pad across the entire peripheries. [Item 5] The electronic component according to any one of Items 1 to 4, where the resin film covers the periphery of the first pad and the periphery of the second pad integrally. [Item 6] The electronic component according to any one of Items 1 to 5, including a high voltage conducting layer formed on the insulating layer, a low voltage conducting layer formed on the insulating layer at an interval from the high voltage conducting layer, a front surface insulating film formed on the insulating layer such as to cover the high voltage conducting layer and the low voltage conducting layer integrally and having high voltage side pad openings exposing portions of the high voltage conducting layer as the high voltage pads and a low voltage side pad opening exposing a portion of the low voltage conducting layer as the low voltage pad,

and where the resin film is formed on the front surface insulating film. [Item 7] The electronic component according to Item 6, where the resin film overlaps with the high voltage conducting layer at a periphery of the high voltage pad openings to demarcate the first pad and overlaps with the high voltage conducting layer at a periphery of the high voltage pad openings to demarcate the second pad. [Item 8] The electronic component according to any one of Items 1 to 7, where the formation region of the high voltage coil includes a coil inner region surrounded by the high voltage coil, the first pad faces the coil inner region in the thickness direction, and the second pad faces, in the thickness direction, a coil outer region outside the high voltage coil. [Item 9] The electronic component according to any one of Items 1 to 8, where the resin film includes a polyimide. [Item 10] The electronic component according to any one of Items 1 to 9, where the resin film has a thickness of not less than 3000 nm and not more than 5000 nm. [Item 11] The electronic component according to any one of Items 1 to 10, where a lateral direction distance L1 between the high voltage pad and the low voltage pad is greater than a vertical direction distance L2 between the high voltage coil and the low voltage coil. [Item 12] The electronic component according to Item 11, where the lateral direction distance L1 is not less than 100 μm and not more than 450 μm and the vertical direction distance L2 is not less than 12.0 μm and not more than 16.8 μm . [Item 13] The electronic component according to any one of Items 1 to 12, further including a withstand voltage enhancement structure of conductive property formed inside the insulating layer and along the high voltage coil such as to protrude further outside than the low voltage coil in plan view. [Item 14] The electronic component according to Item 13, where the withstand voltage enhancement structure includes a dummy pattern extending along the high voltage coil in a pattern that is discontinuous to a spiral pattern of the high voltage coil. [Item 15] The electronic component according to Item 14, where the dummy pattern has a shape with ends. [Item 16] The electronic component according to Item 14 or 15, where the high voltage coil includes an inner terminal end and an outer terminal end and the dummy pattern is fixed to be equipotential to the outer terminal end of the high voltage coil. [Item 17] The electronic component according to Item 16, where the inner terminal end of the high voltage coil is positioned in a region at an inner side of the low voltage coil in plan view, the outer terminal end of the high voltage coil is positioned in a region outside the low voltage coil in plan view, and the dummy pattern is led out from the outer terminal end of the high voltage coil. [Item 18] The electronic component according to any one of Items 1 to 12, further including a pad side withstand voltage enhancement structure of conductive property formed inside the insulating layer such as to be oriented along a peripheral edge of the second pad of the high voltage pads in plan view. [Item 19] The electronic component according to Item 18, where the pad side withstand voltage enhancement structure includes a pad side dummy pattern extending along the peripheral edge of the second pad in a pattern discontinuous to the spiral pattern of the high voltage coil in plan view. [Item 20] The electronic component according to Item 19, where the pad side withstand voltage enhancement structure includes a plurality of the pad side dummy patterns formed at intervals along a direction away from the second pad. [Item 21] The electronic component according to Item 19, where a distance between the pad side dummy pattern most proximal to the second pad and the second pad is not more than a vertical direction distance between the high voltage coil and the low voltage coil. [Item 22] The electronic component according to any one of Items 18 to 21, further including a coil side withstand voltage enhancement structure of conductive property formed inside the insulating layer and along the high voltage coil and protruding further outside than the low voltage coil in plan view. [Item 23] The electronic component according to Item 22, where the coil side withstand voltage enhancement structure is fixed to be equipotential to the pad side withstand voltage enhancement structure. [Item 24] The electronic component according to any one of Items 1 to 12, including a low voltage wiring formed inside the insulating layer at an interval from the high voltage coil in a direction along a front surface of the insulating layer, electrically connected to the low voltage coil, and forming, with the high voltage coil, an electric field having a first value not more than a dielectric breakdown

strength of the insulating layer, an electric field enhancement structure interposed in a region inside the insulating layer between the high voltage coil and the low voltage wiring and forming, with the low voltage wiring, an electric field having a second value not more than the dielectric breakdown strength of the insulating layer and not less than the first value, and a second insulating layer formed on the insulating layer such as to cover the high voltage pads and the low voltage pad and having a dielectric breakdown strength not more than the dielectric breakdown strength of the insulating layer. [Item 25] The electronic component according to Item 24, where the electric field enhancement structure includes a high voltage side dummy pattern of conductive property fixed to be equipotential to the high voltage coil and formed along the high voltage coil. [Item 26] The electronic component according to Item 24 or 25, where the electric field enhancement structure includes a low voltage side dummy pattern of conductive property fixed to be equipotential to the low voltage wiring and formed along the low voltage wiring. [Item 27] The electronic component according to any one of Items 24 to 26, where the dielectric breakdown strength of the insulating layer is not less than 5.0 MV/cm and the dielectric breakdown strength of the second insulating layer is not less than 1.0 MV/cm. [Item 28] The electronic component according to any one of Items 24 to 27, where the second insulating layer is constituted of a resin layer. [Item 29] The electronic component according to Item 28, where the resin layer includes a molded resin. [Item 30] An electronic component module including the electronic component according to any one of Items 1 to 29 and a resin package sealing the electronic component. [Item 31] The electronic component module according to Item 30, further including a low voltage device electrically connected to the low voltage coil of the electronic component and a high voltage device electrically connected to the high voltage coil of the electronic component, and where the resin package seals the electronic component, the low voltage device, and the high voltage device altogether.

(448) The present application claims priority based on Japanese Patent Application No. 2017-199877 filed in the Japan Patent Office on Oct. 13, 2017 and the entire disclosure of this application is incorporated herein by reference.

(449) While preferred embodiments of the present invention have been described in detail, these are merely specific examples used to clarify the technical contents of the present invention and the present invention should not be interpreted as being limited to these specific examples and the scope of the present invention is to be limited only by the appended claims.

DESCRIPTION OF SYMBOLS

(450) **1** electronic component module **2** resin pattern **5** controller chip **6** electronic component **7** driver chip **13** low voltage pad **14** high voltage pad **20** lower coil (low voltage conductor pattern) **21** upper coil (high voltage conductor pattern) **27** insulating layer laminated structure **28** insulating layer (first insulating layer) **32** inner region (of upper coil) **33** first pad **34** second pad **39** first region **40** second region **44** overlapping portion **45** overlapping portion **50** inter-coil region **75** protective film **76** passivation film **77** resin film **78** pad opening **79** pad opening **88** high voltage pad layer **89** low voltage pad layer **99** coil periphery region **101** electronic component **102** withstand voltage enhancement structure **103** first withstand voltage enhancement structure **104** second withstand voltage enhancement structure **108** first dummy conductor pattern **116** first coil side withstand voltage enhancement structure **117** second coil side withstand voltage enhancement structure **118** first pad side withstand voltage enhancement structure **119** second pad side withstand voltage enhancement structure **131** electronic component **141** electronic component **142** first spiral pattern **143** second spiral pattern **151** electronic component **152** second insulating layer **161** electronic component **162** low voltage side capacitor conductor film (low voltage conductor pattern) **163** high voltage side capacitor conductor film (high voltage conductor pattern) **164** first capacitance **165** second capacitance **171** electronic component **201** electronic component module

Claims

1. An electronic component comprising: an insulating layer; a low voltage conductor pattern formed inside the insulating layer; a high voltage conductor pattern formed inside the insulating layer such as to face the low voltage conductor pattern in an up/down direction; a low voltage pad formed on the insulating layer and electrically connected to the low voltage conductor pattern; a high voltage pad formed on the insulating layer at an interval from the low voltage pad in plan view and electrically connected to the high voltage conductor pattern; and a conductor pattern formed inside the insulating layer and arranged along the low voltage pad between the low voltage pad and the high voltage pad in plan view.
 2. The electronic component according to claim 1, wherein; the low voltage conductor pattern includes a low voltage coil having a spiral shape, the high voltage conductor pattern includes a high voltage coil having a spiral shape, and a transformer is formed by the low voltage coil and the high voltage coil.
 3. The electronic component according to claim 1, wherein the conductor pattern is arranged closer to the low voltage pad than the high voltage pad in plan view.
 4. The electronic component according to claim 1, further comprising a resin film formed on the insulating layer along a peripheral edge of the high voltage pad in sectional view.
 5. The electronic component according to claim 3, wherein the conductor pattern has a line shaped pattern extending along a first direction in plan view.
 6. The electronic component according to claim 5, wherein the first direction intersects a second direction which is a direction between the low voltage pad to the high voltage pad in plan view.
 7. The electronic component according to claim 5, wherein the conductor pattern includes a dummy conductor pattern that is discontinuous with respect to the high voltage conductor pattern.
 8. The electronic component according to claim 7, wherein the dummy conductor pattern has a shape having ends.
 9. The electronic component according to claim 4, further comprising: a passivation film formed between the insulating layer and the resin film, wherein the passivation film overlaps a part of the high voltage pad in the up/down direction.
 10. The electronic component according to claim 9, further comprising: a protective film formed between the insulating layer and the passivation film, wherein the protective film overlaps a part of the high voltage pad in the up/down direction.
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